



สถาบันมาตรวิทยาแห่งชาติ
National Institute of Metrology (Thailand)

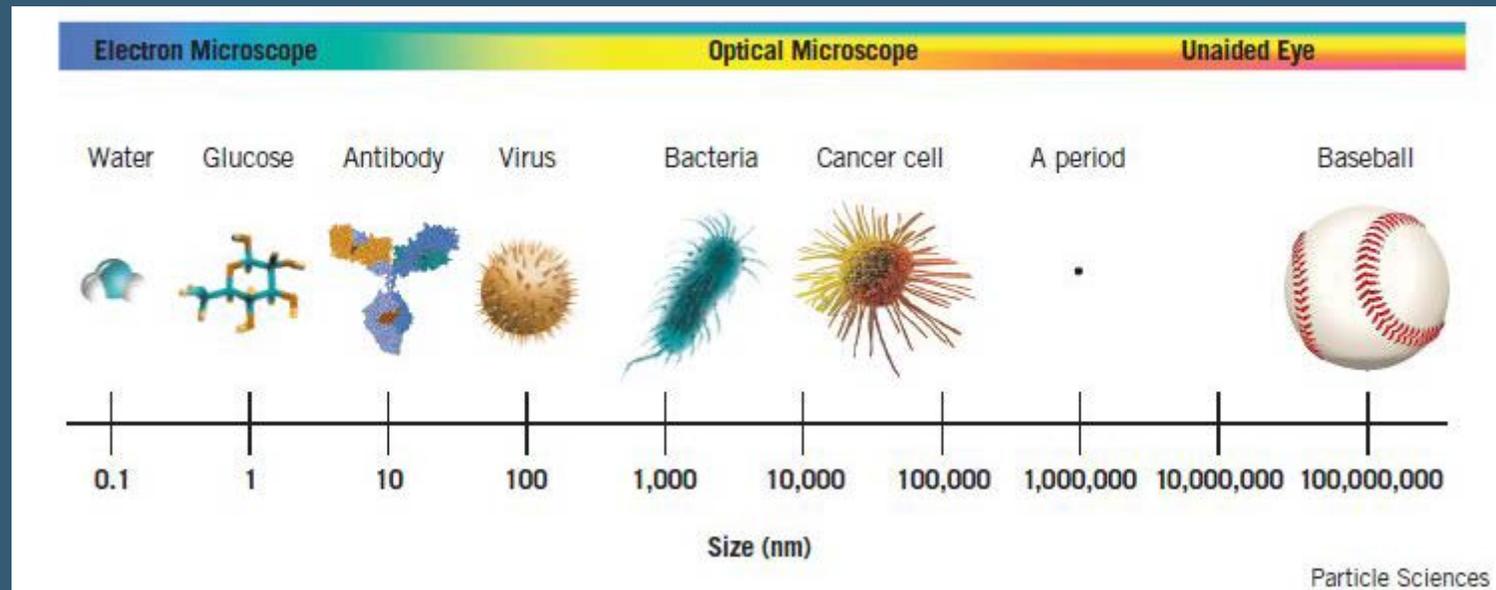


MATERIAL CHARACTERIZATION TECHNIQUE FOR NANO-SCALE MEASUREMENT

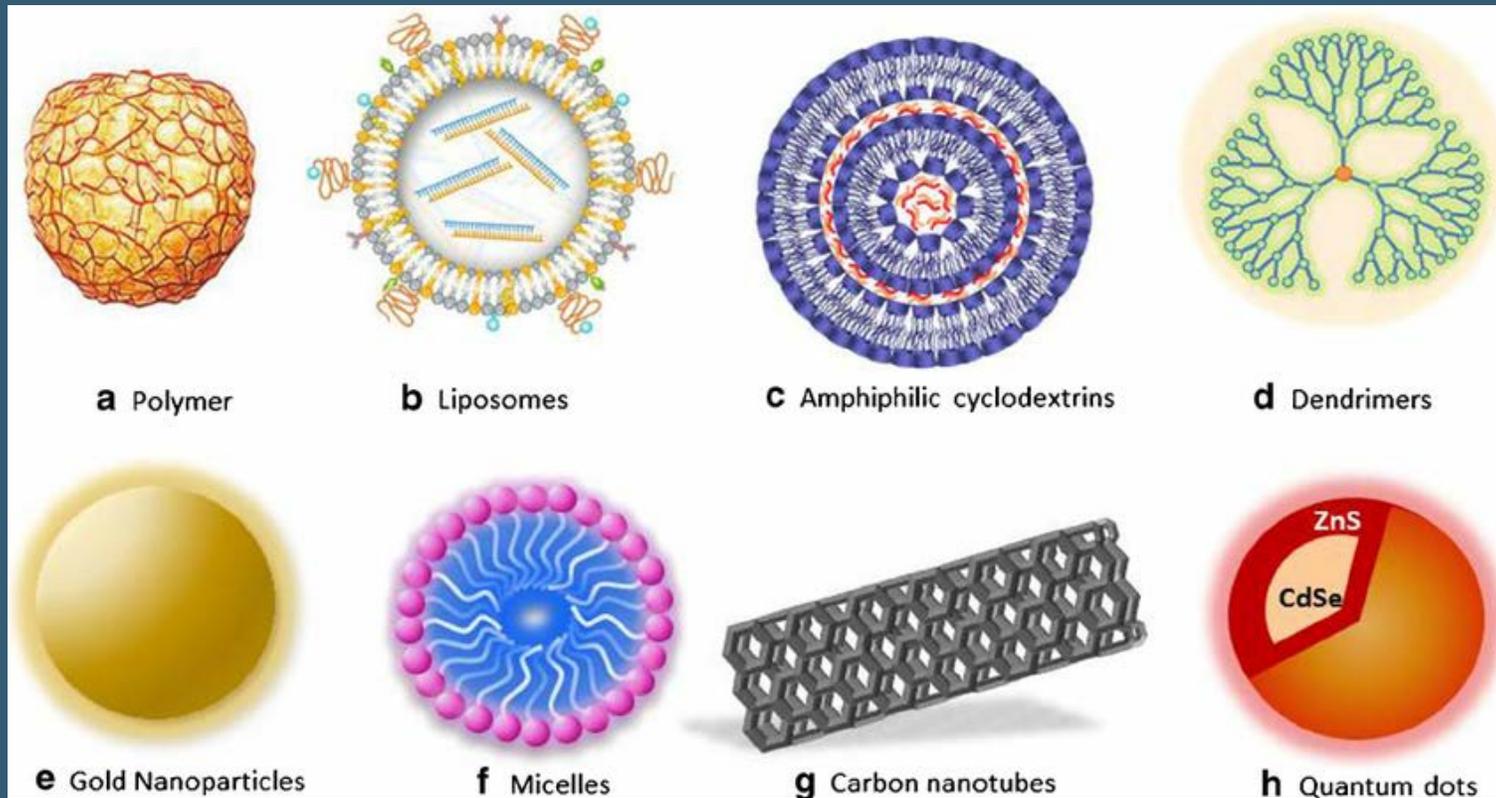
Dr Jariya Buajarern

Nanometrology Group, Dimensional Metrology Department

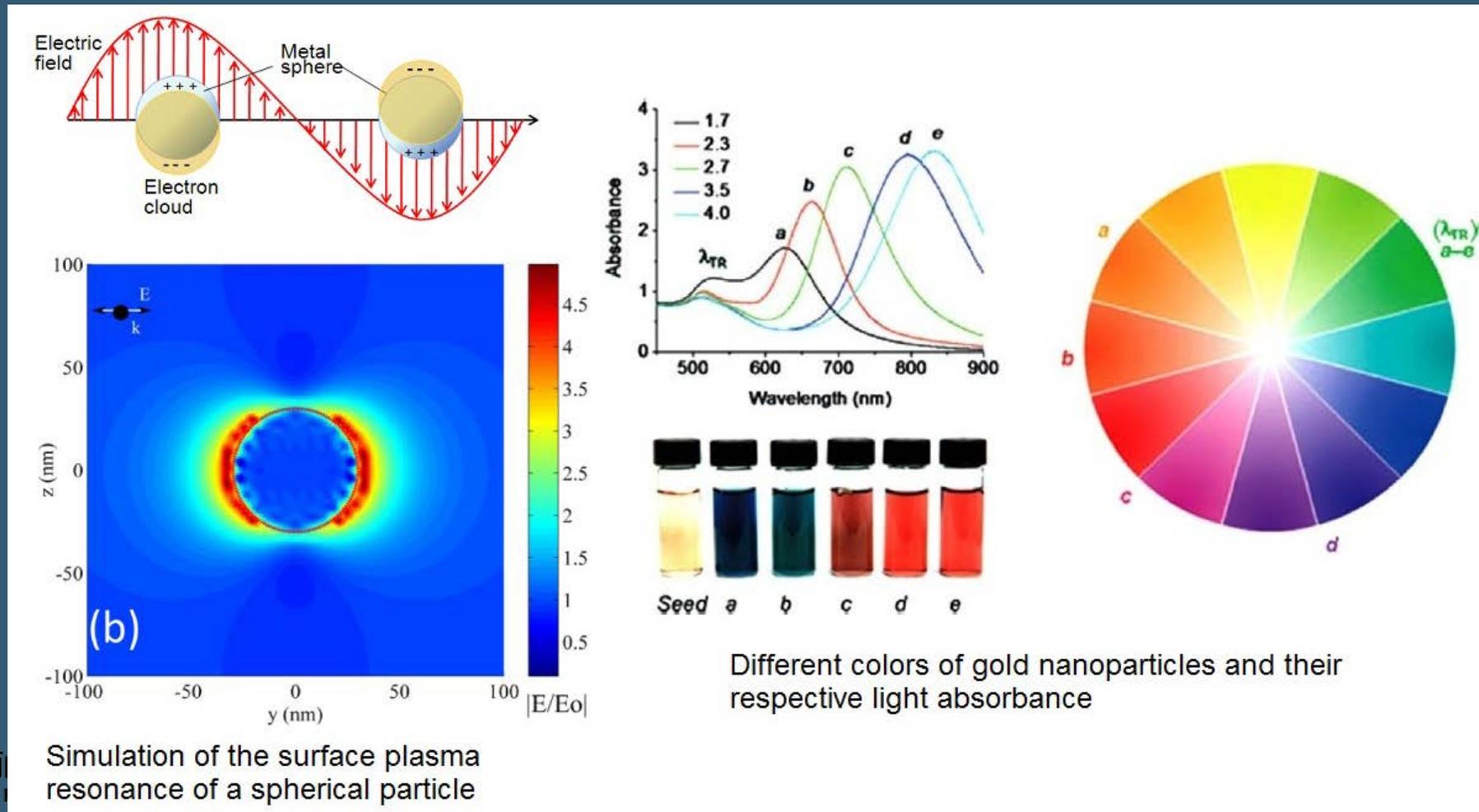
NANOSCALE



NANOPARTICLES



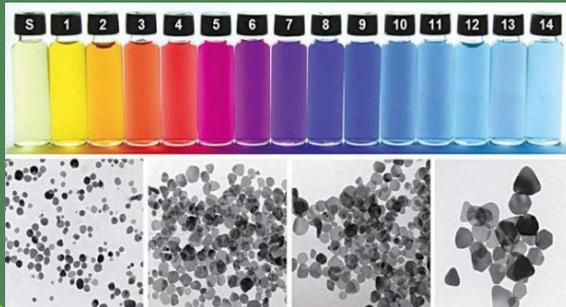
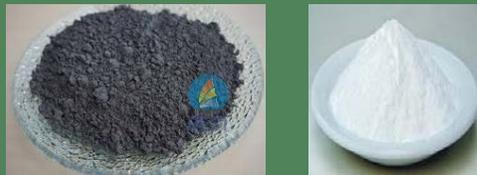
PROPERTIES



NANOTECHNOLOGY VALUE CHAIN

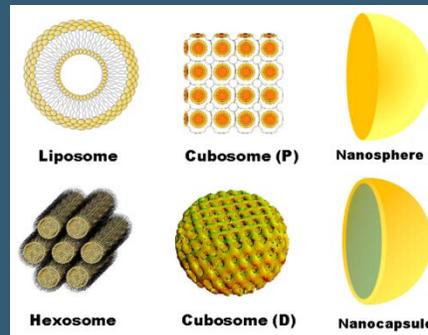
Nanomaterial

Nanoscale structures in unprocessed form



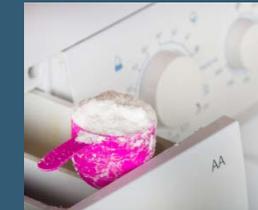
Nanointermediates

Intermediate products with nanoscale features



Nano-enable products

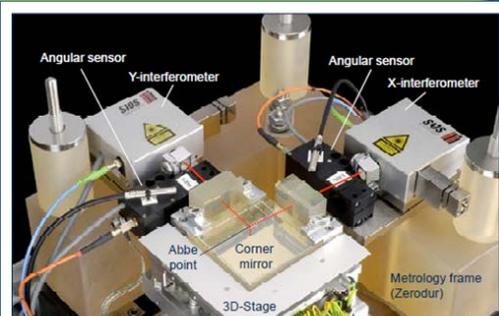
Finished goods incorporating nanotechnology



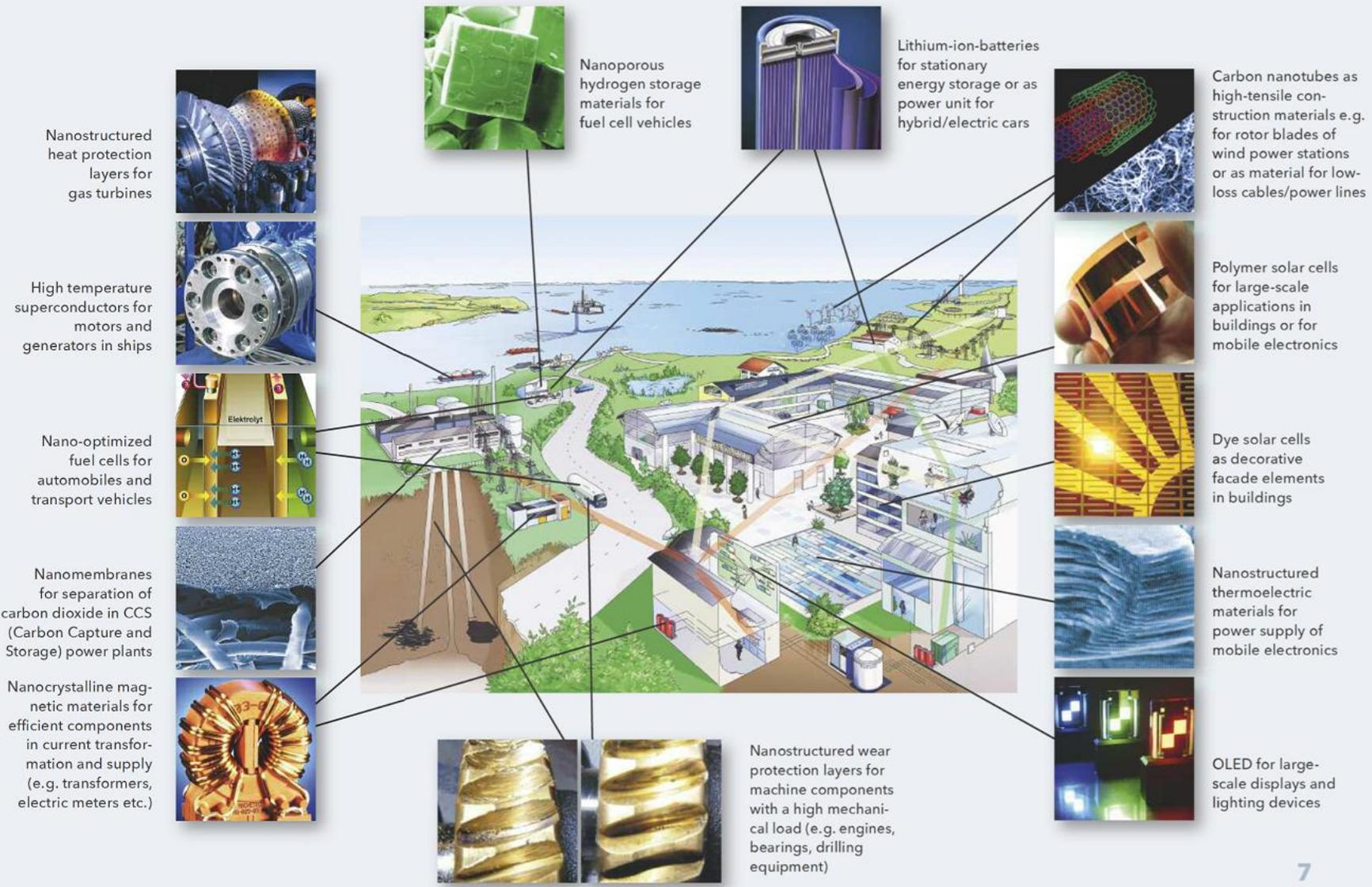
Needs!!!

Measurement methods, Instruments, Standards, Safety

ผลิตภัณฑ์ที่มีส่วนประกอบของวัสดุนาโน หรือใช้นาโนเทคโนโลยีเพื่อสร้างคุณลักษณะใหม่ ทั้งนี้ลักษณะของวัสดุนาโนที่เติมลงไป ในผลิตภัณฑ์อาจมีโครงสร้างที่ซับซ้อน และแตกต่างจากวัสดุนาโนในรูปของวัตถุดิบ ดังนั้นการพิสูจน์ว่าผลิตภัณฑ์มีวัสดุนาโนอยู่จริง และปลอดภัย จึงเรื่องท้าทาย



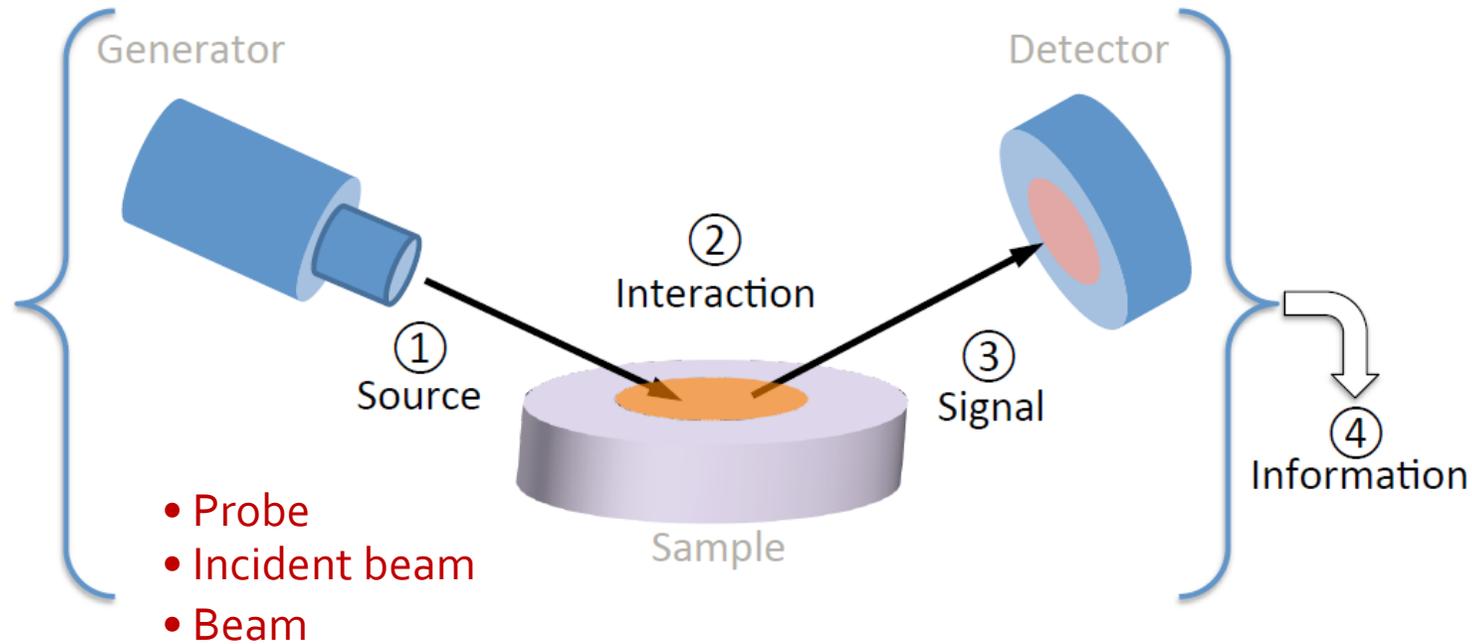
มว. สถาบันระบบการสอบกลับได้ในการวัดวัสดุนาโนตั้งแต่ ปีพ.ศ.2558 และเปิดให้บริการสอบเทียบมาตรฐานสำหรับเครื่องทดสอบขนาดวัสดุนาโน



CHARACTERIZATION TECHNIQUES

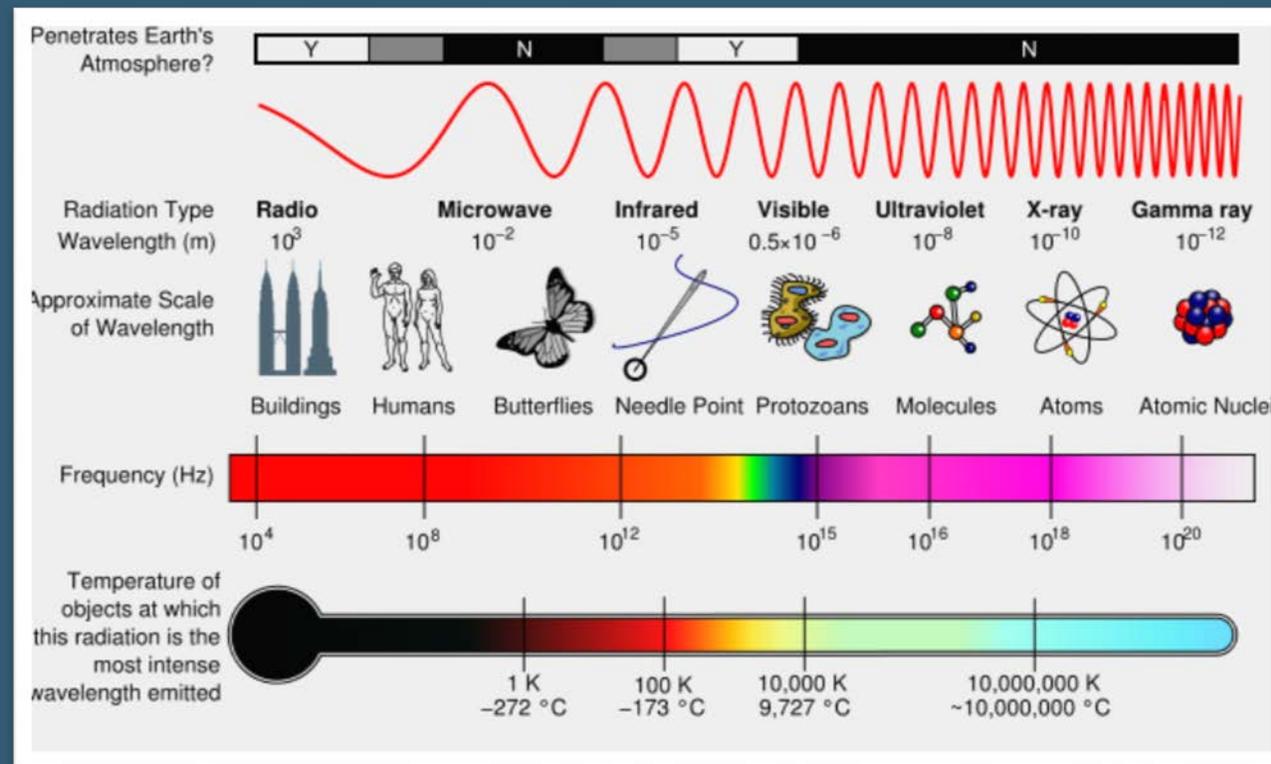
Properties	Common Techniques
Size (primary particle)	TEM, SEM, AFM, XRD
Size (primary/aggregate/agglomerate)	TEM, SEM, AFM, DLS, FFF, AUC, CHDF, XDC, HPLC, DMA(1)
Size distribution	EM, SEM, AFM, DLS, AUC, FFF, HPLC, SMA
Molecular weight	SLS, AUC, GPC
Structure/Shape	TEM, SEM, AFM, NMR
Stability (3D structure)	DLS, AUC, FFF, SEM, TEM

BASIC PRINCIPLE

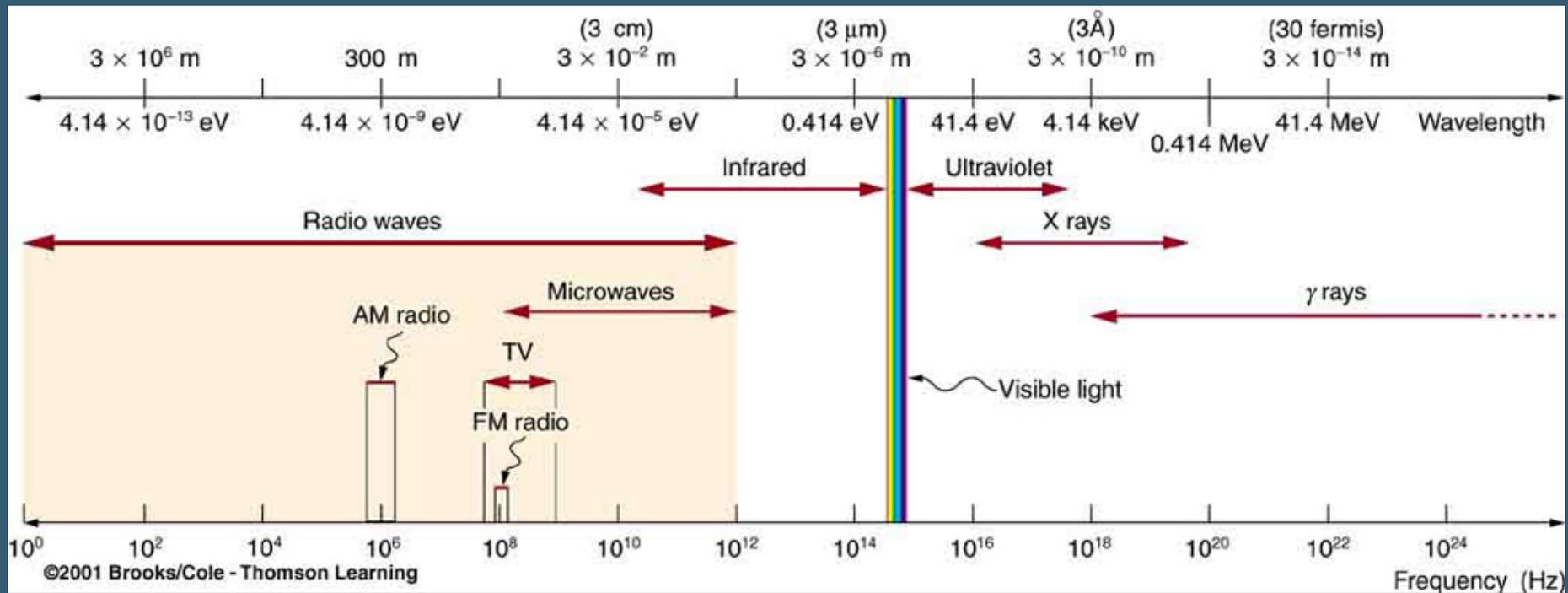


- ① A source radiation is aimed at the sample
- ② It interacts with the sample in some way
- ③ As a result of the interaction, a signal is produced
- ④ Analysis of the signal reveals information about the sample

ELECTRO-MAGNETIC RADIATION (PHOTONS)



PHOTON ENERGY IN EV

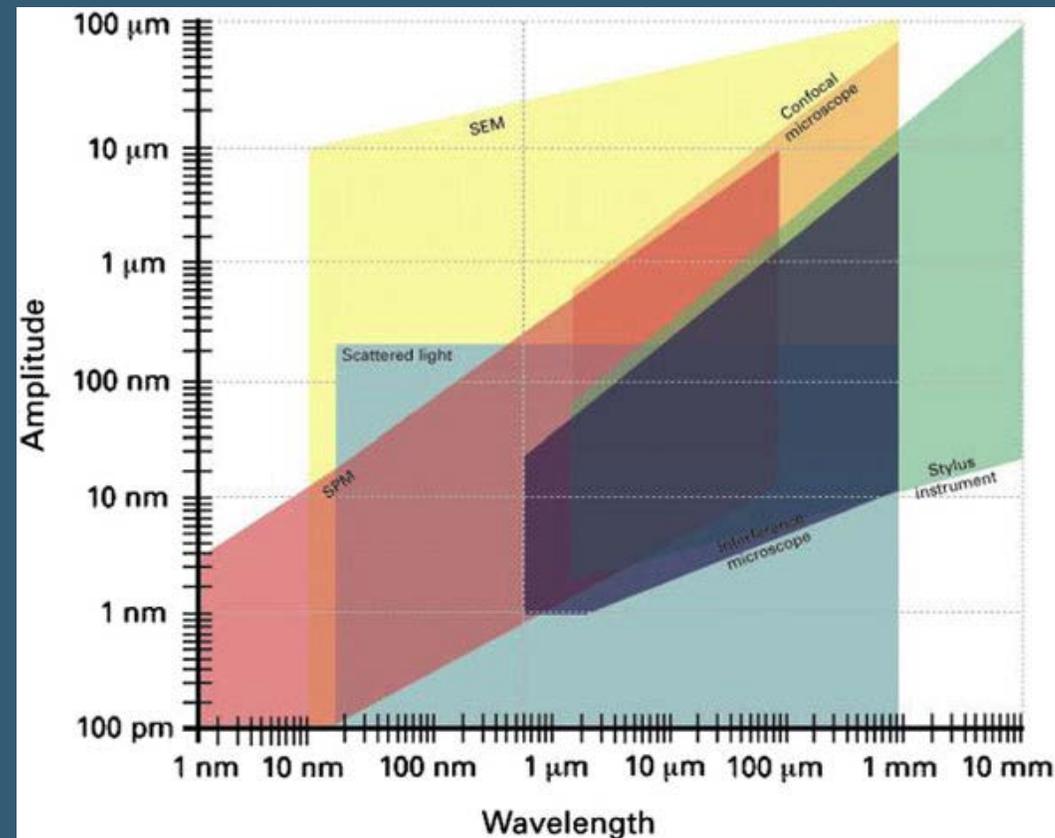


CATEGORIES OF TECHNIQUES

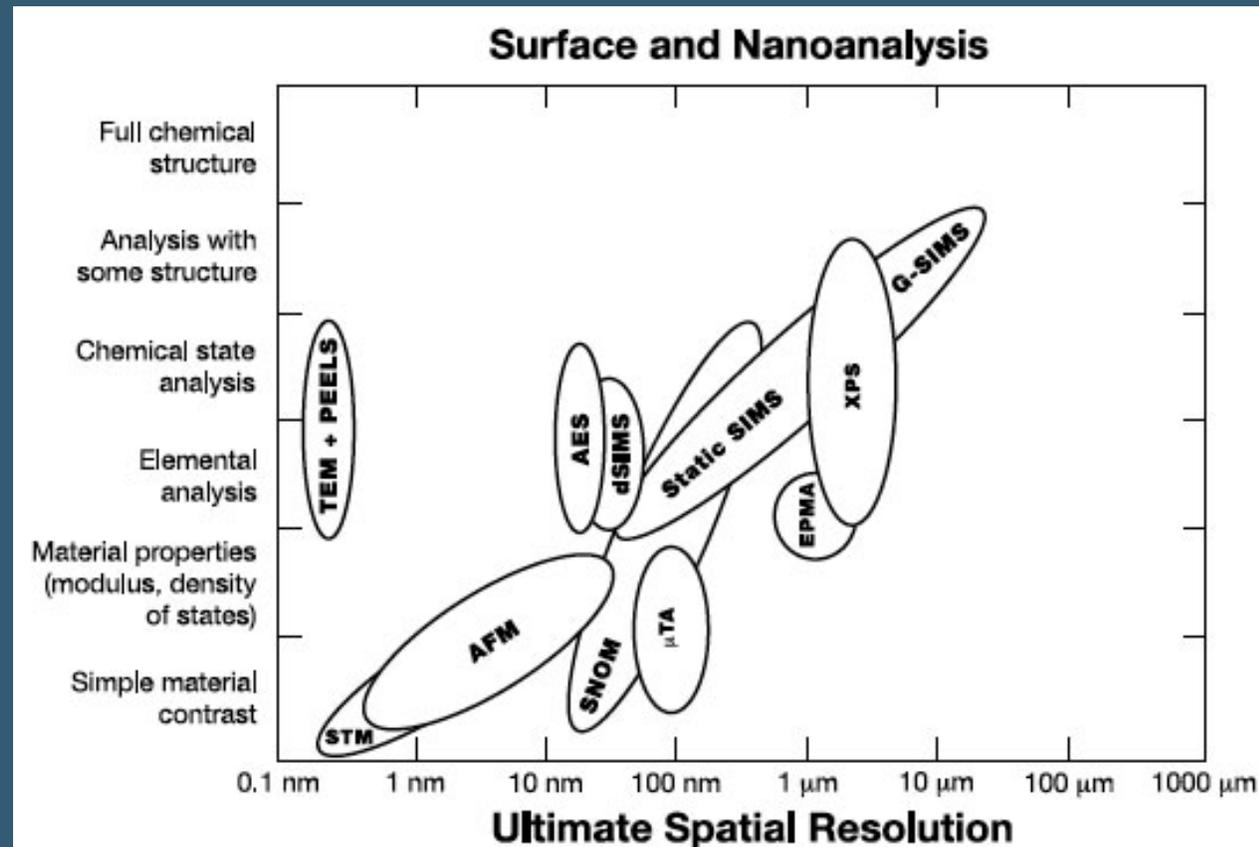
- Microscopy (imaging)
- Diffraction (crystal structure)
- Spectroscopy (chemical composition/elemental analysis)

CHARACTERIZATION TECHNIQUES: DIMENSIONAL NANOMETROLOGY

• Spatial resolution = $\frac{0.611 \cdot \lambda}{NA}$



CHARACTERIZATION TECHNIQUES: CHEMICAL NANOMETROLOGY



TRANSMISSION ELECTRON MICROSCOPE (TEM)

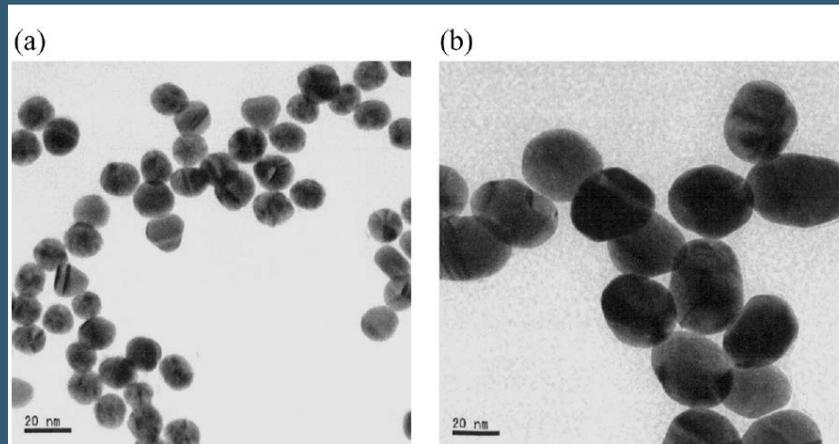
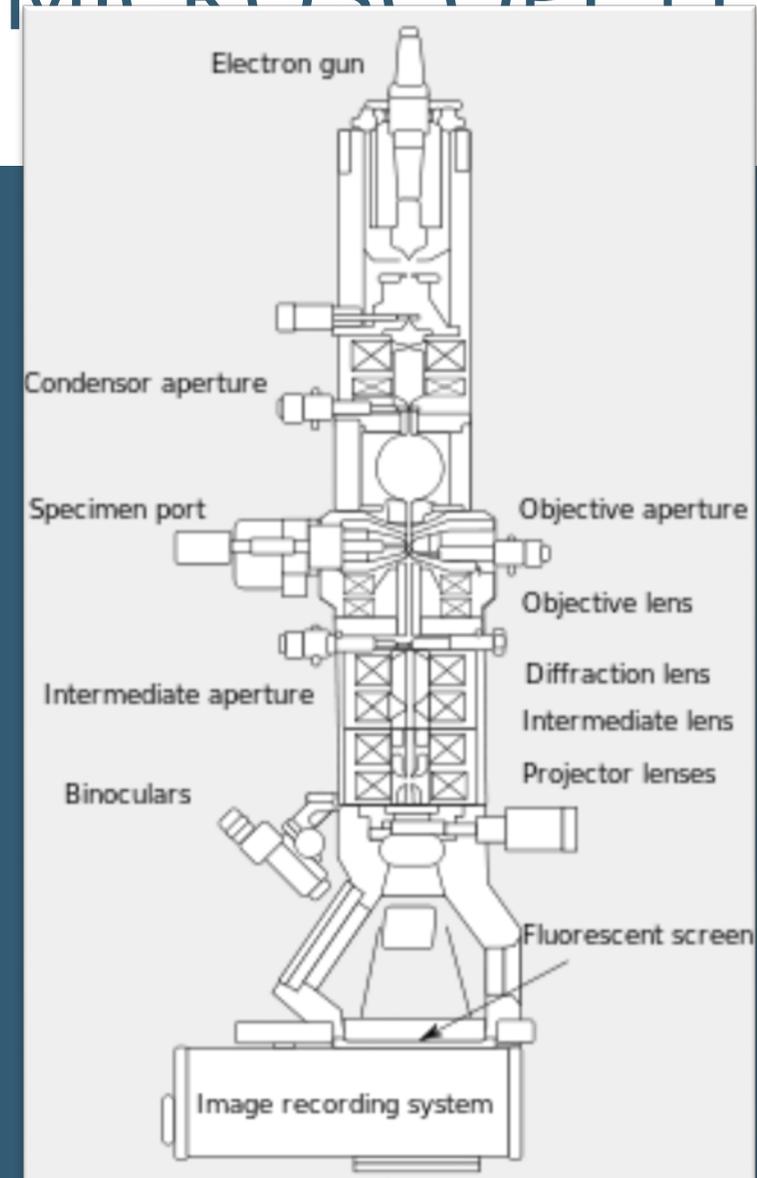
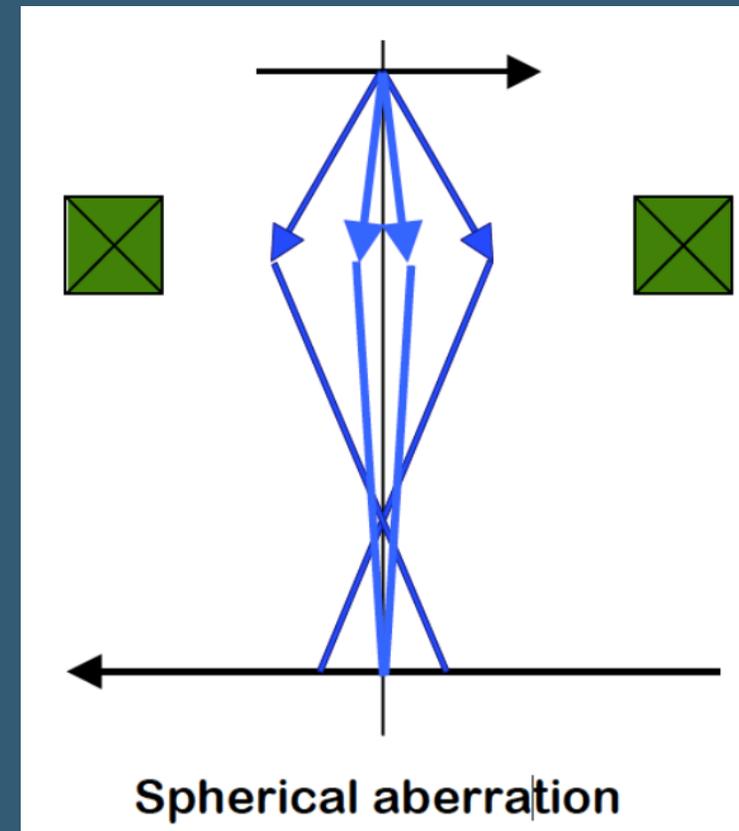


Fig. 1. TEM images of gold nanoparticles.
(a) Au 15 nm, (b) Au 35 nm.

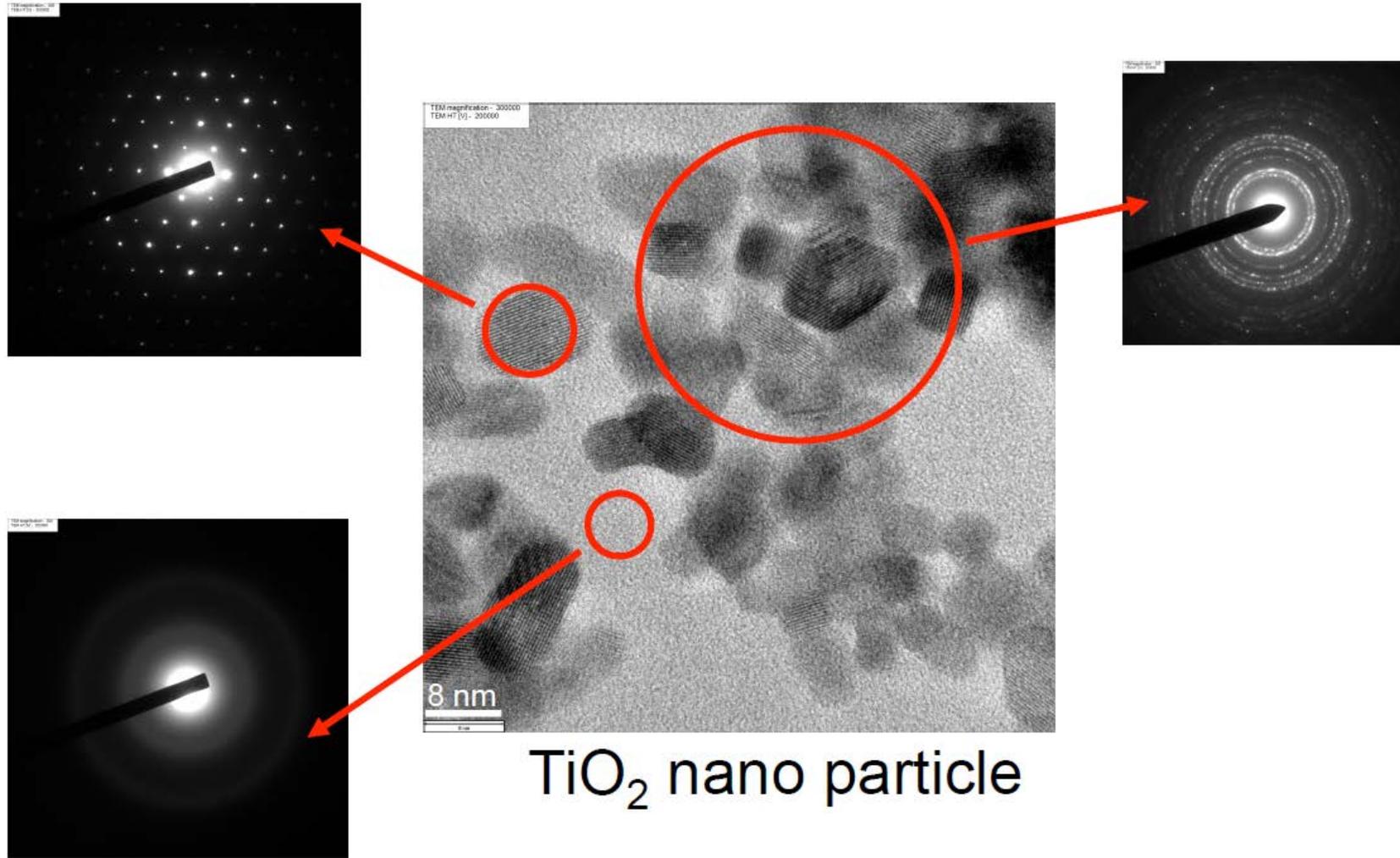


PARAMETERS THAT AFFECT IMAGE RESOLUTION

- Wavelength
- Spherical aberration
- Diffraction vector
- Defocus

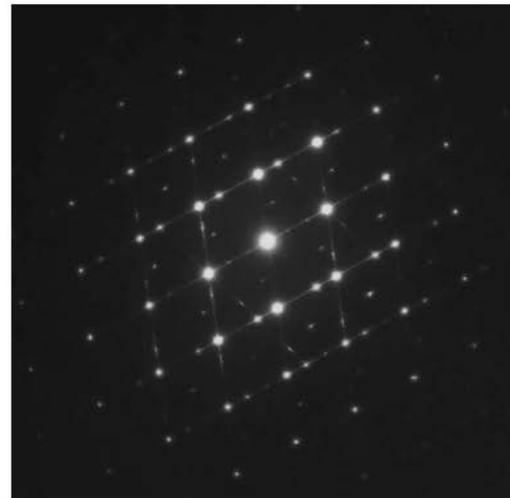
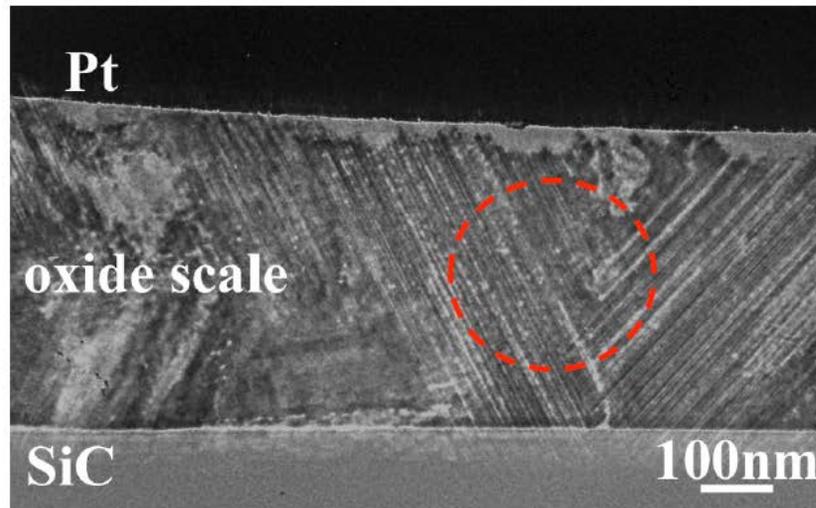


Electron Diffraction Pattern

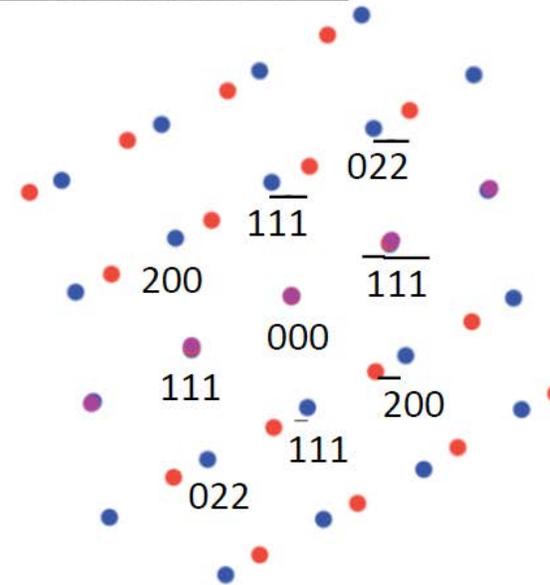


TiO_2 nano particle

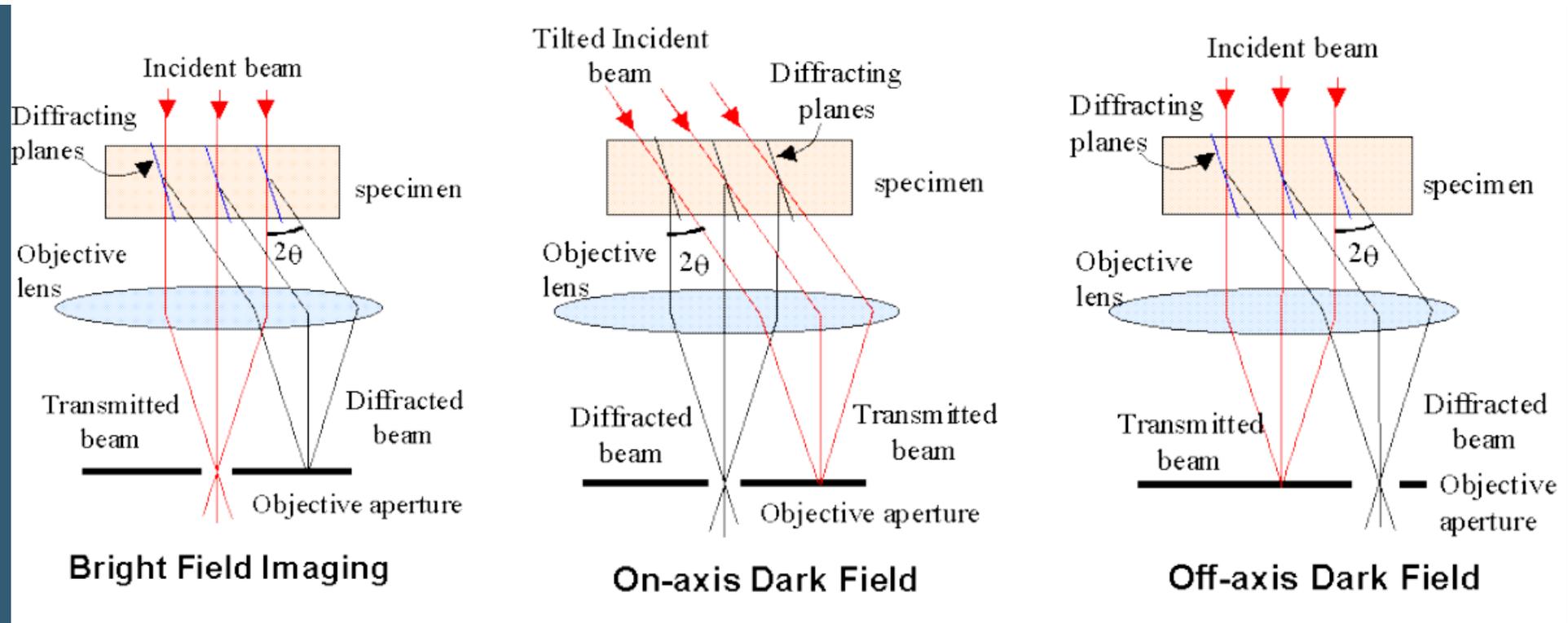
Electron Diffraction Pattern of Twin Crystal



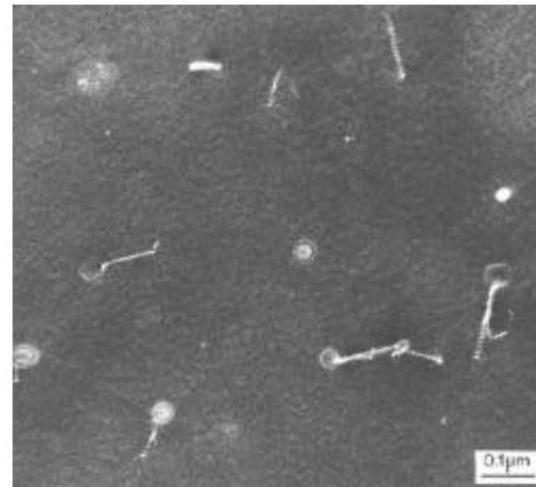
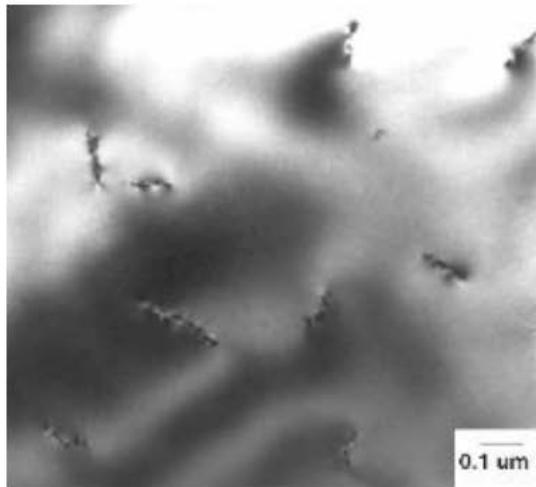
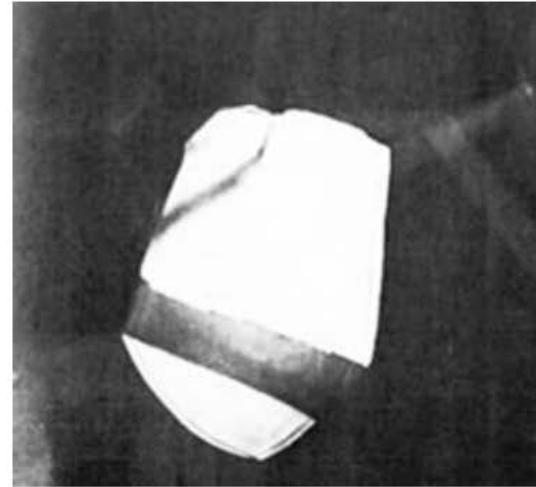
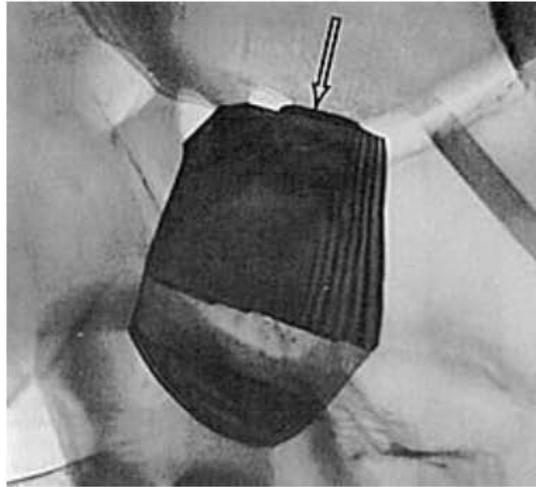
Cristobalite (high)



Bright-field and Dark-field Imaging

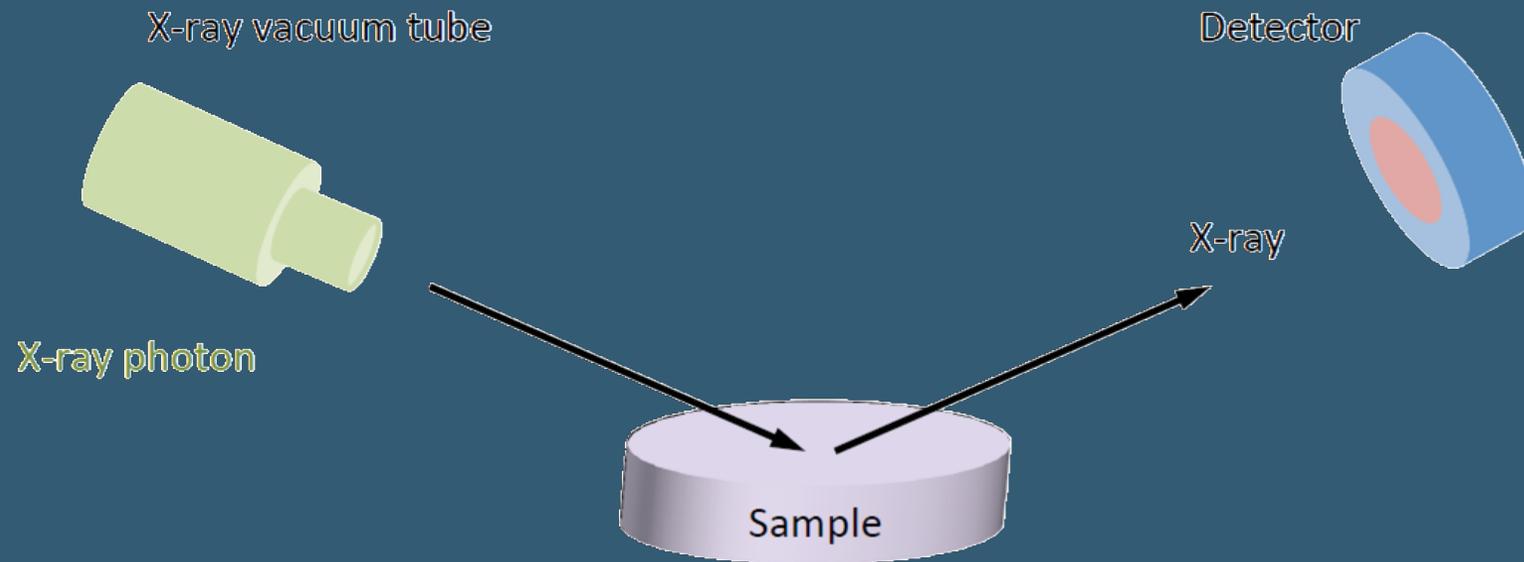


Advantages of dark field imaging



X-RAY DIFFRACTION (XRD)

- Incident beam X-ray
- Diffraction
- Detected beam X-ray

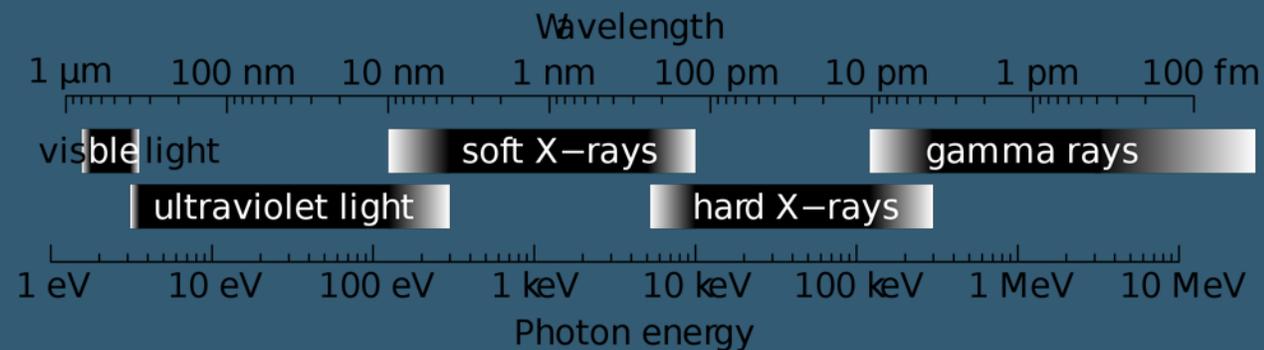


PRINCIPLES

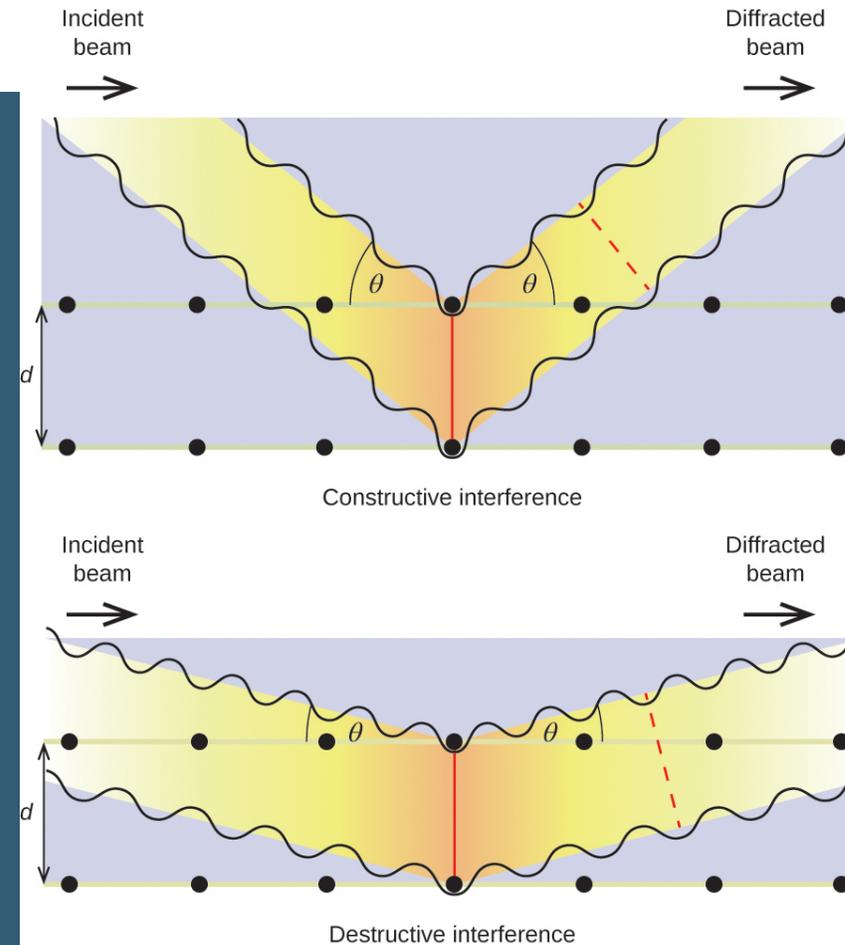
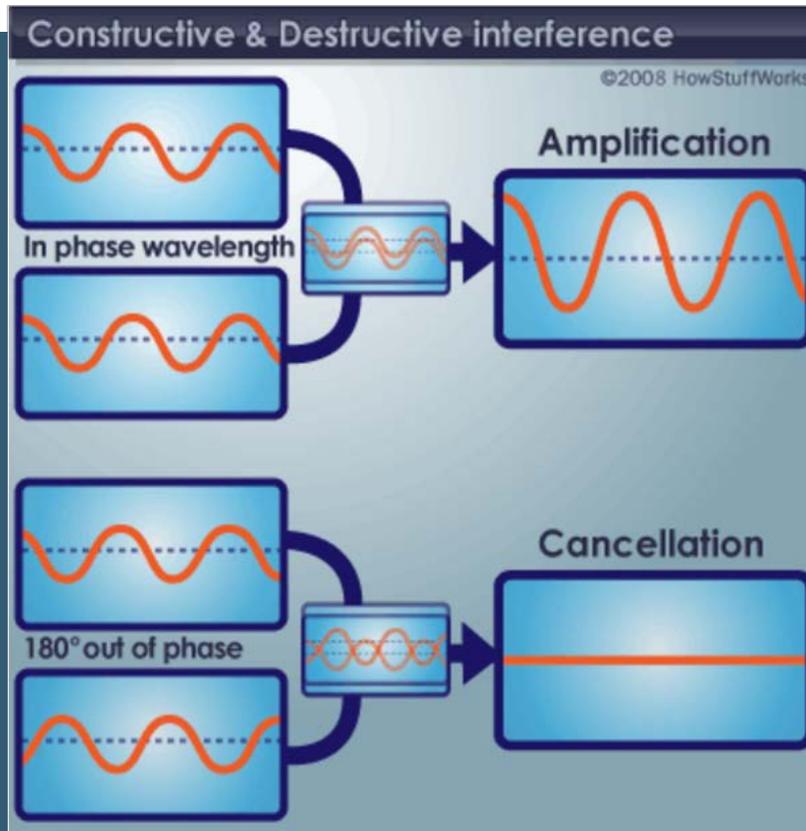
- Diffraction = scattering from regular spacing
- This gives interference (Diffraction pattern) or peaks
- Crystal structure is regular arrangement
- Crystal structure + lattice parameter = finger print of the material
- Diffraction pattern = finger print

WHAT WE CAN GET FROM XRD

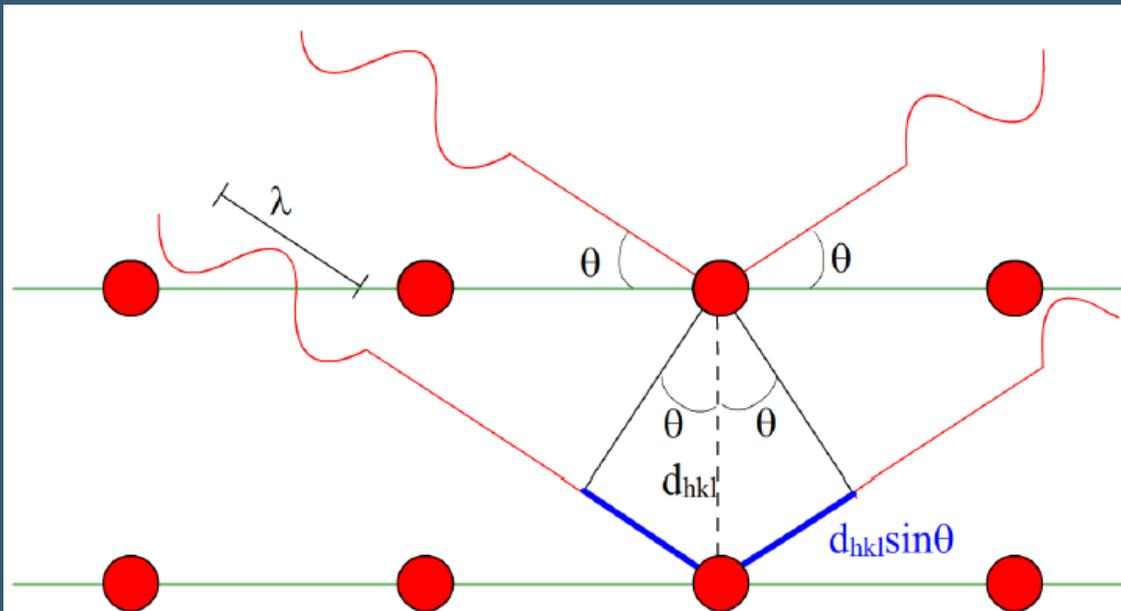
- Crystal structure (FCC, BCC,)
- D-spacing (0.1-0.3 nm) and lattice parameters
- Orientation
- Phase information (FeO or Fe₂O₃)
- Internal stresses



INTERACTION (DIFFRACTION)



BRAGG'S LAW



Total path difference = $2d_{hkl}\sin\theta$

Constructive Interference when $n\lambda = 2d_{hkl}\sin\theta$

<http://www.doitpoms.ac.uk/tlplib/xray-diffraction/flash/bragg.swf>

Jointly awarded the 1915
Nobel Prize in Physics



William Henry Bragg



William Lawrence Bragg

$$d_{hkl} = n\lambda / 2 \cdot \sin\theta$$

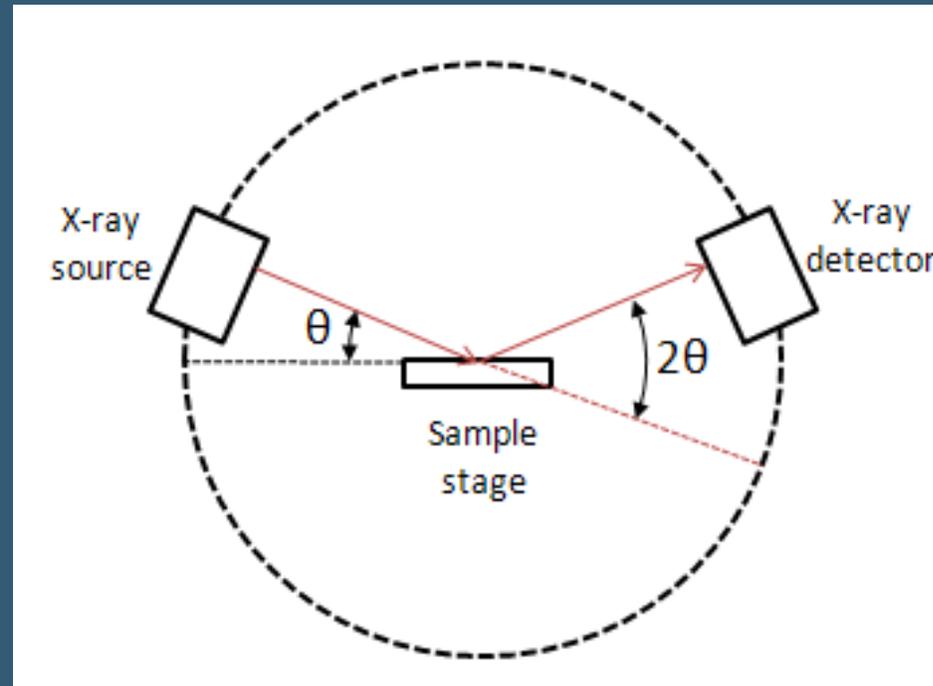
DETECTION

X-Ray can be detected in 2 main ways:

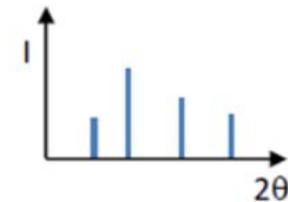
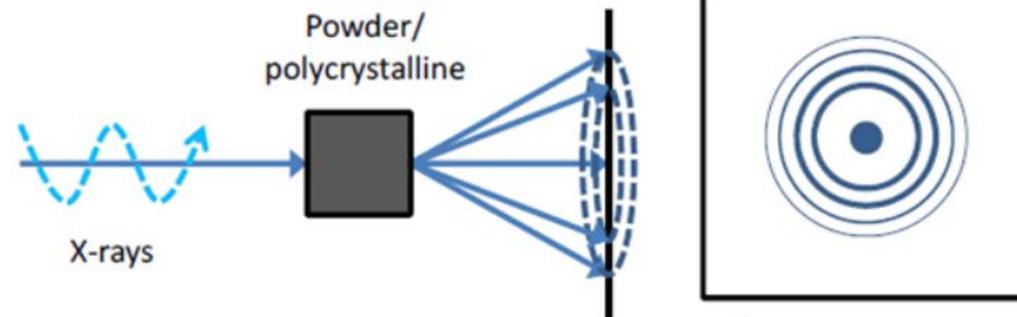
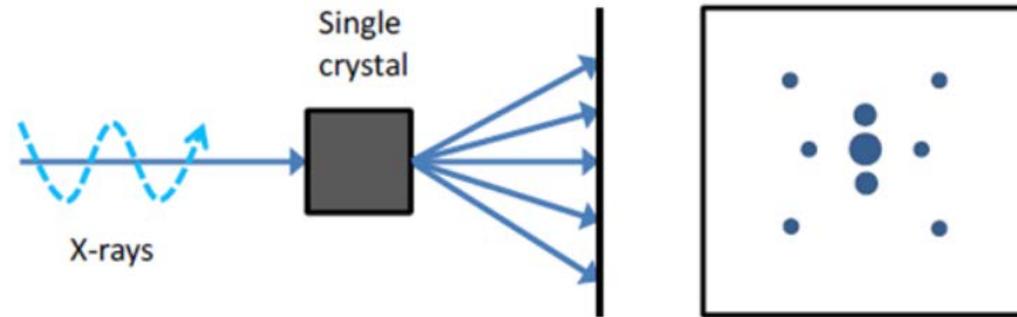
- 1) Measuring blackening produced in **photographic film**. Converts amount of blackening into x-ray intensity
- 2) Measuring pulses of **electric current**. Convert pulses into x-ray intensity

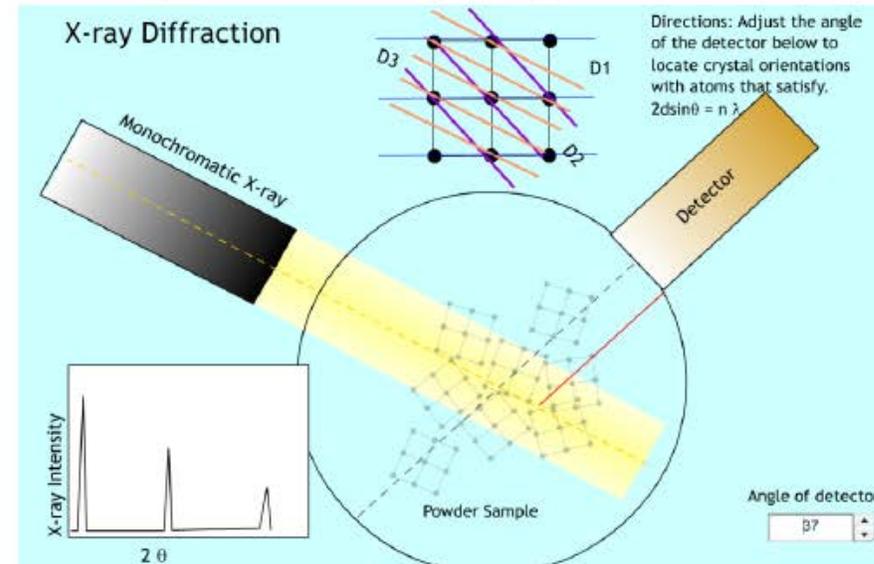
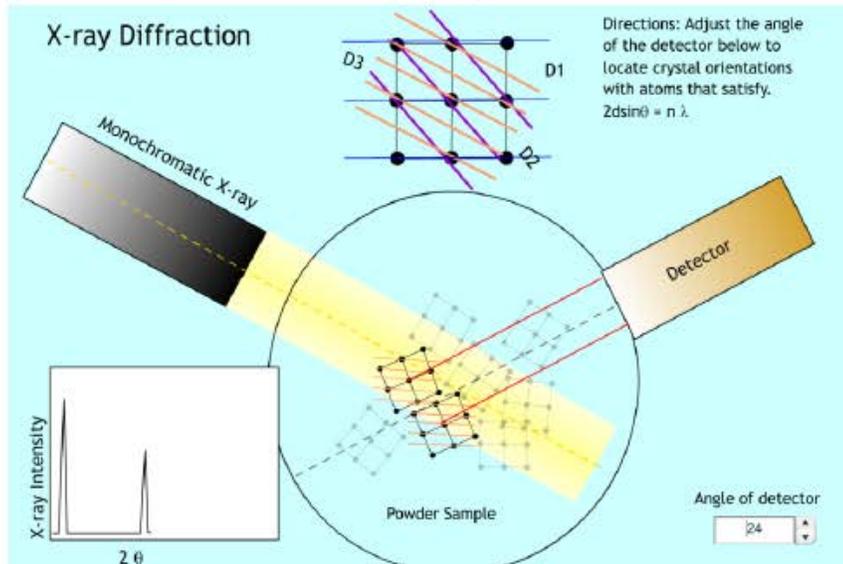
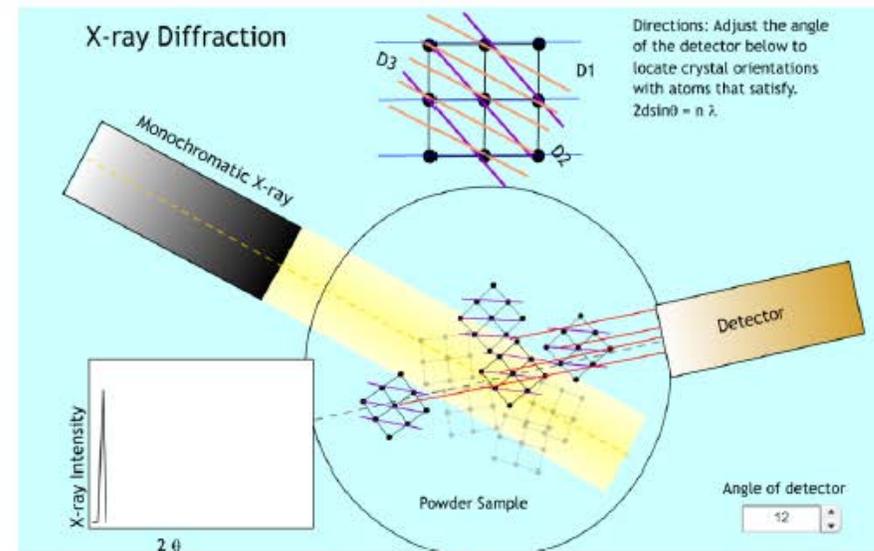
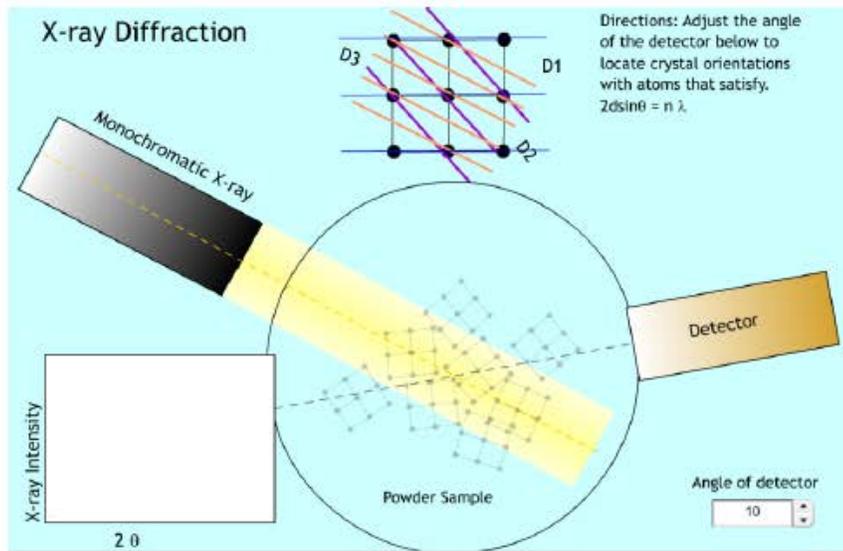
X-RAY DIFFRACTOMETER

- 1) X-ray source
- 2) Interaction
- 3) X-ray detector
- 4) Analysis



DIFFRACTION PATTERN

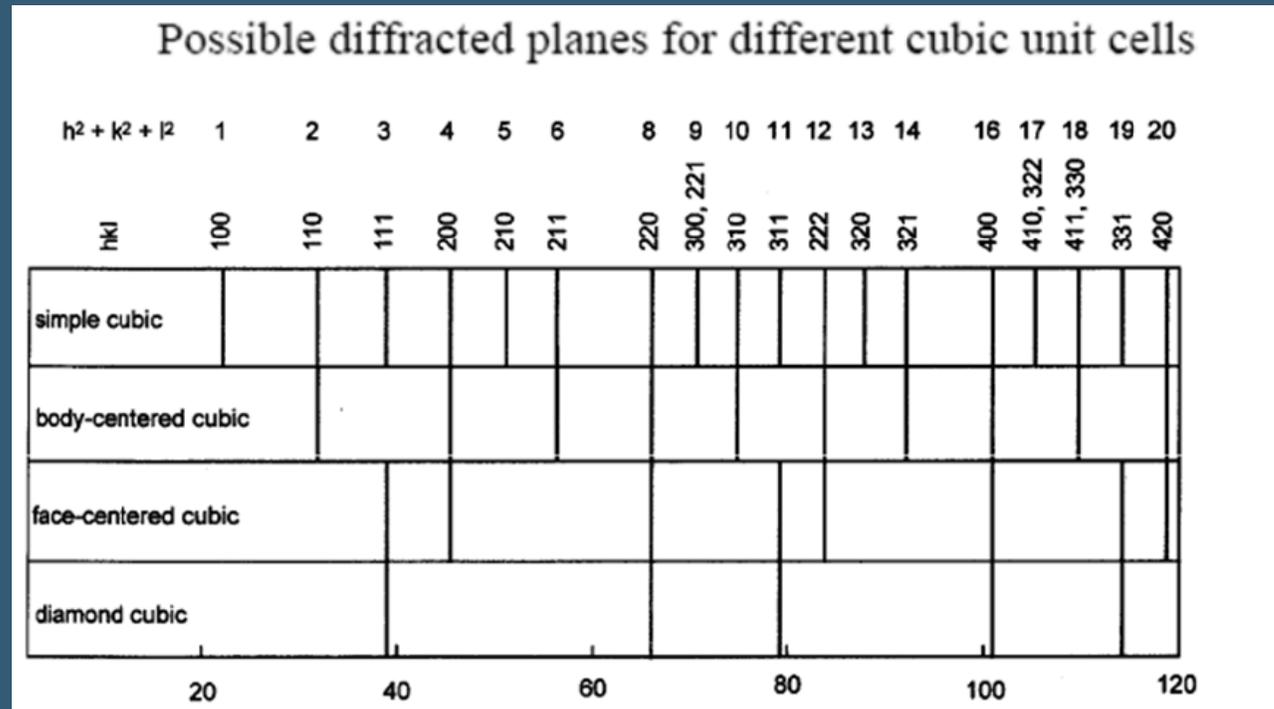




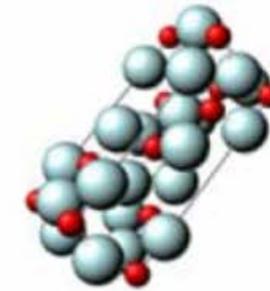
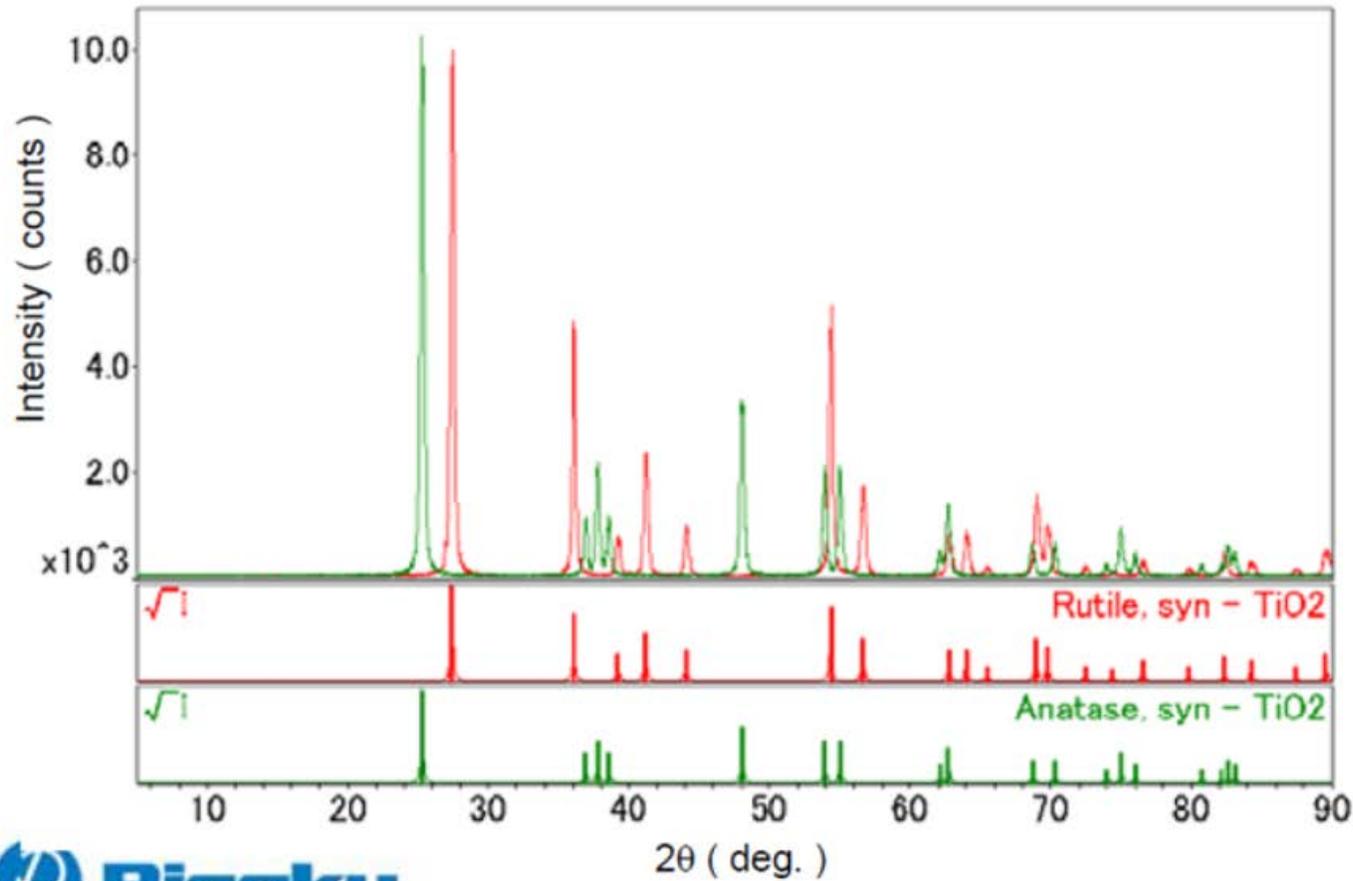
<http://photonicswiki.org/images/4/46/Xrd.swf>

ANALYSIS

- We get from XRD: peaks at 2θ
- We analyze:
 - Peak position (Planes of atoms = Crystal structure)
 - Width
 - Intensity



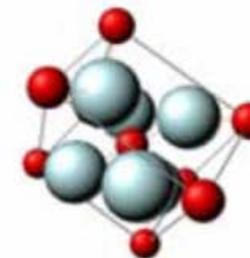
EXAMPLE 1



Anatase

Used For Photocatalyst

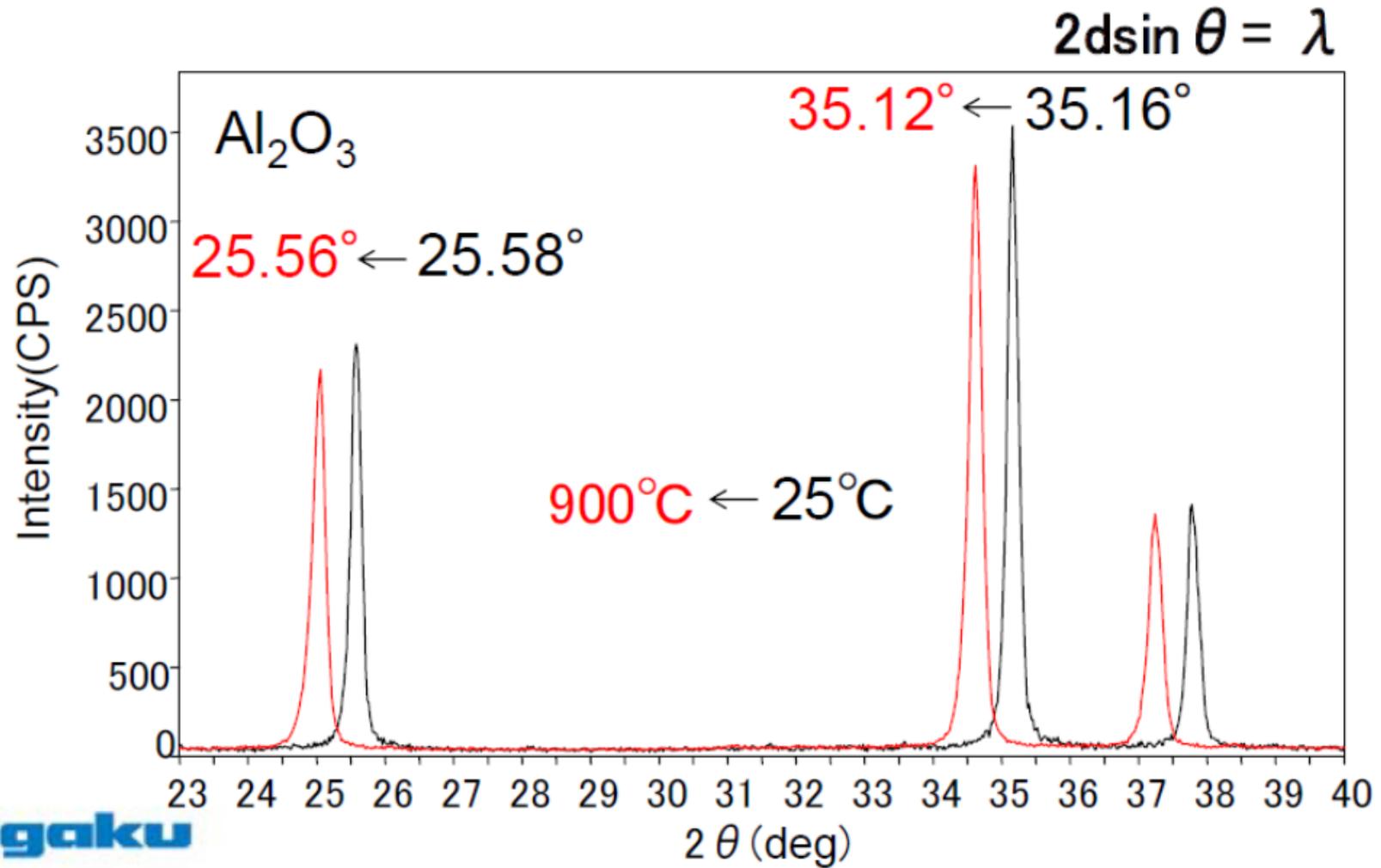
TiO₂



Rutile

Used For Cosmetic

EXAMPLE 2



http://homepage.ntu.edu.tw/~kcyuan/form/For_Rigaku-Upload_powder.pdf

Peak width

Grain size

Internal Strains

- Grain size

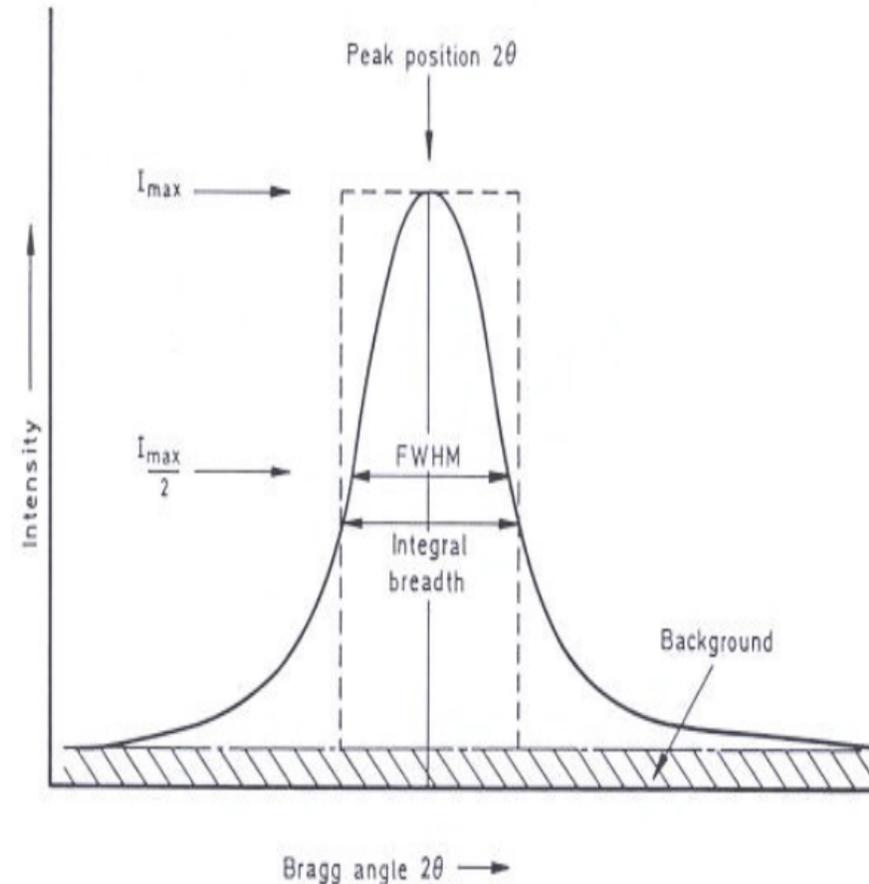
Scherrer Equation

$$B(2\theta) = \frac{K\lambda}{L \cos \theta}$$

Smaller grains wider peak

B: width K: constant

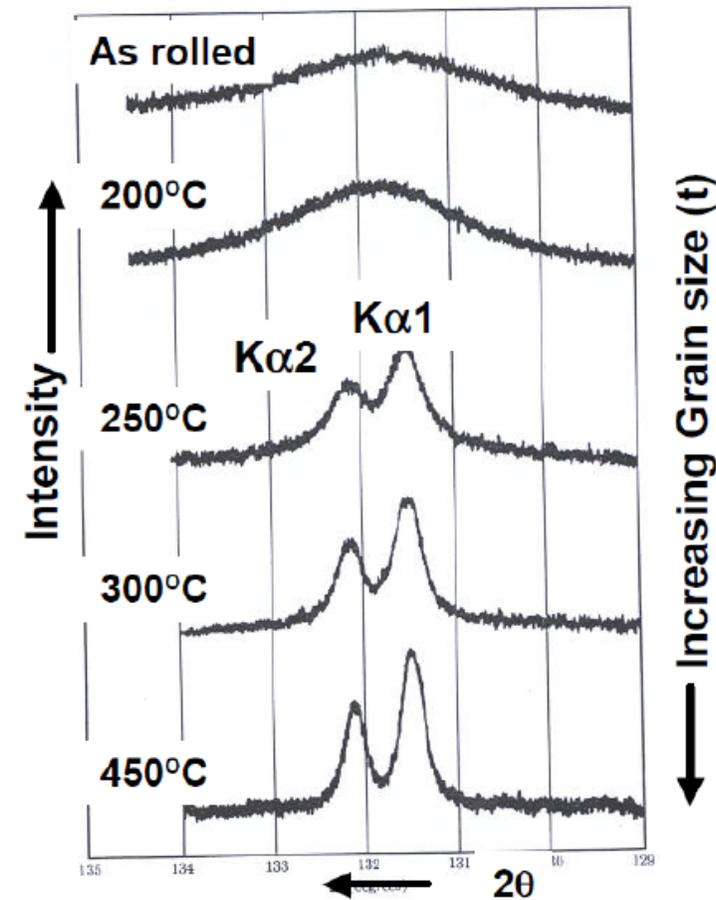
L: grain size



Elements of X-RAY Diffraction By B.D.Cullity and S.R.Stock

EXAMPLE 3

- Rolled material has very small grains \longrightarrow broader peak
- As the material annealed grains start to grow and peak becomes sharper



(331) Peak of cold-rolled and Annealed 70Cu-30Zn (brass)

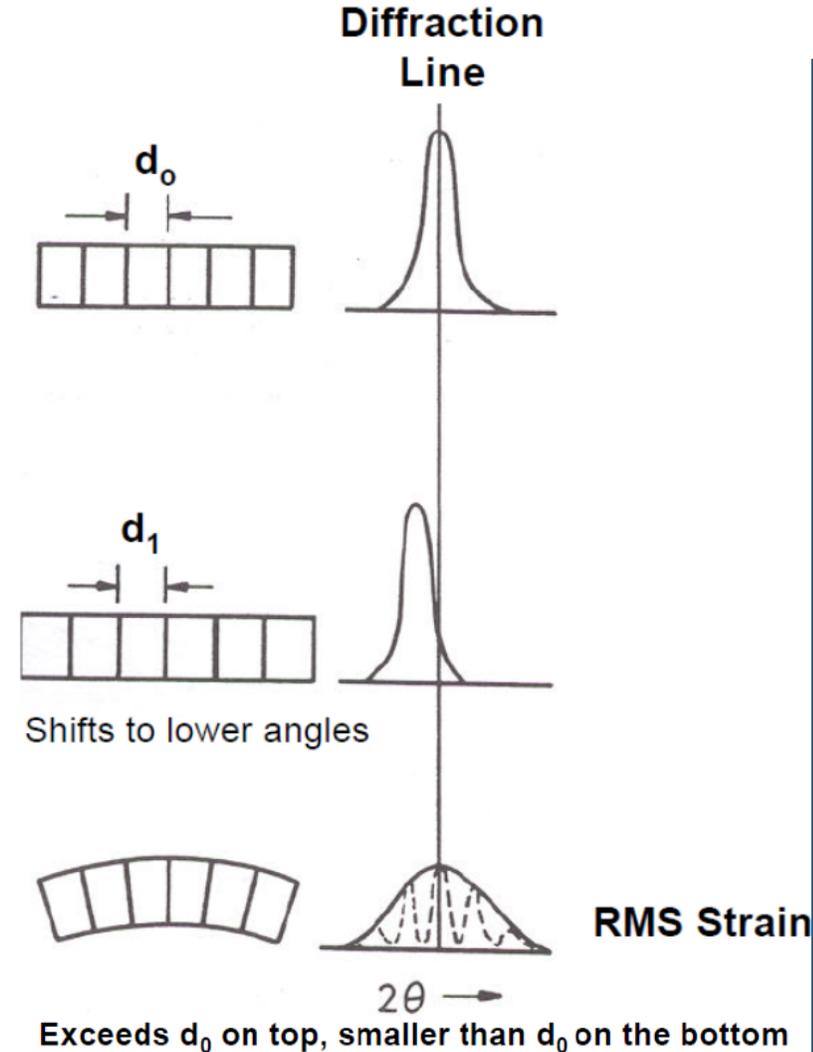
Elements of X-RAY Diffraction By B.D.Cullity and S.R.Stock

EXAMPLE 4

- Internal strain

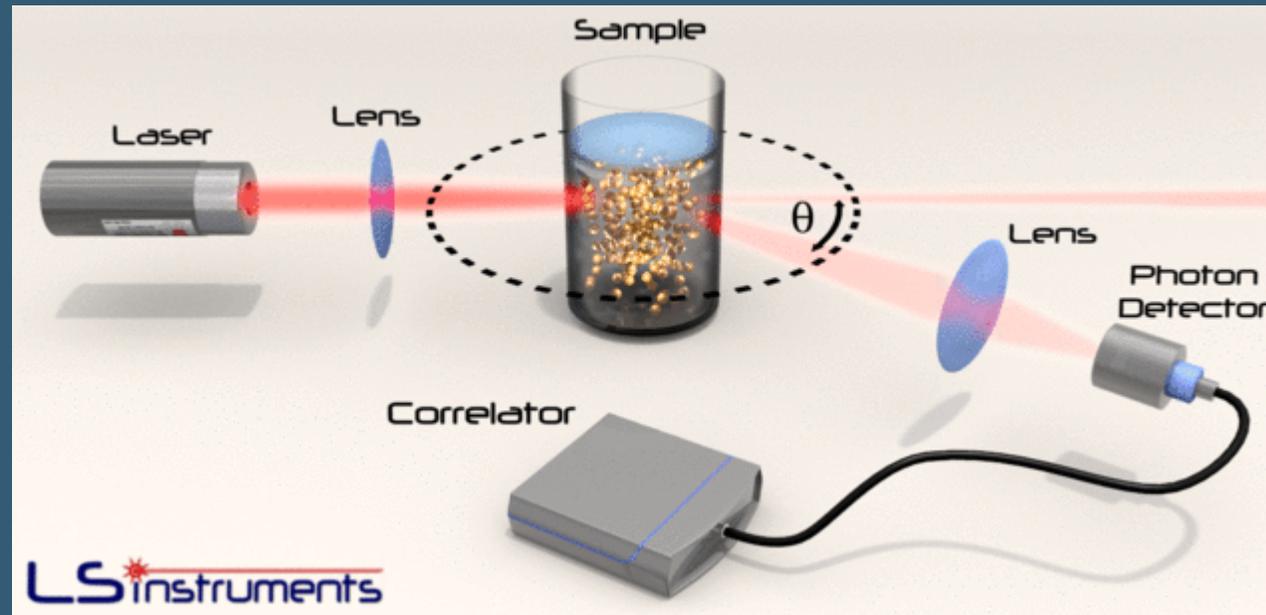
$$2d\sin\theta = \lambda$$

- Tensile stress increase d
- As d increase peak shifts to the right
- Compressive stress decrease d
 - shift peak to the left

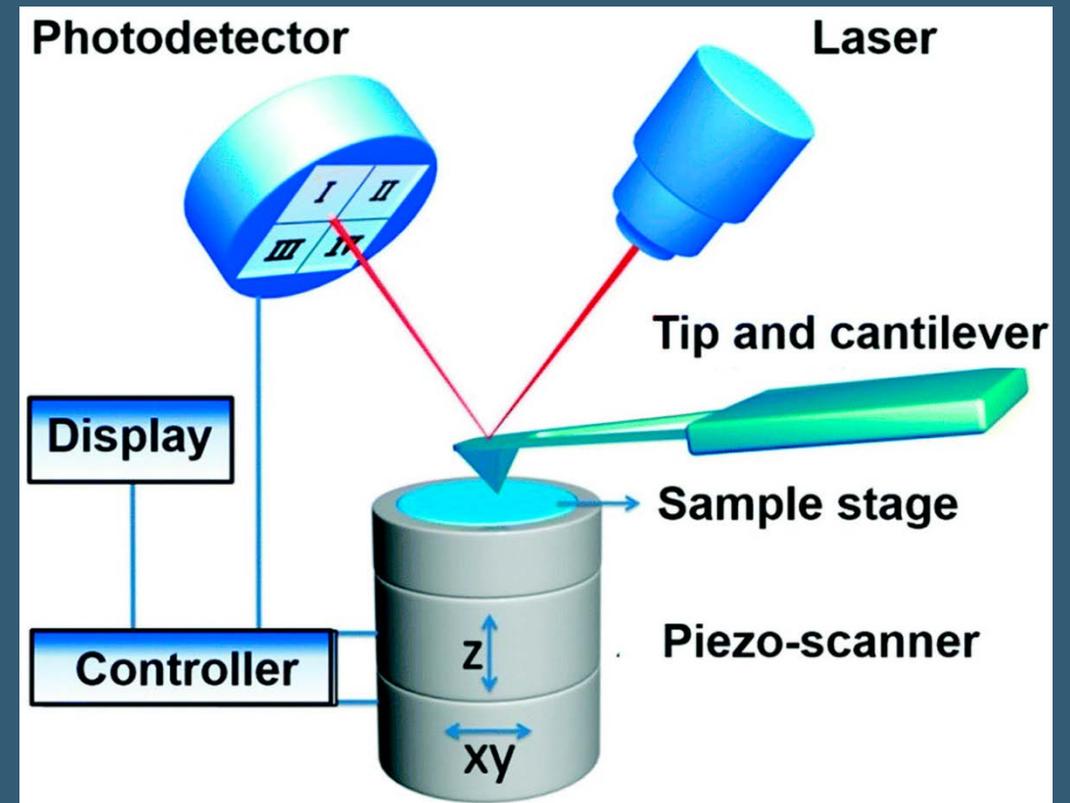
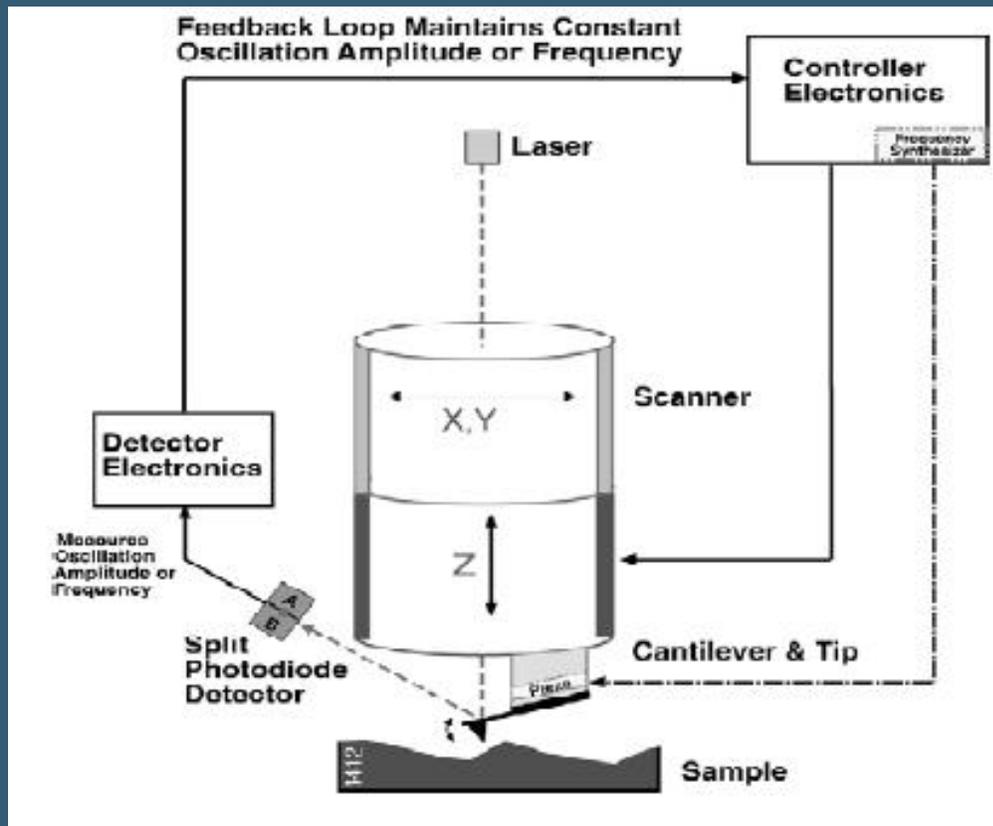


DYNAMIC LIGHT SCATTERING (DLS)

$$R = \frac{k_B T}{6\pi\eta} \cdot \frac{16\pi^2 n^2 \cdot \sin^2(\theta/2)}{\Gamma \cdot \lambda^2}$$

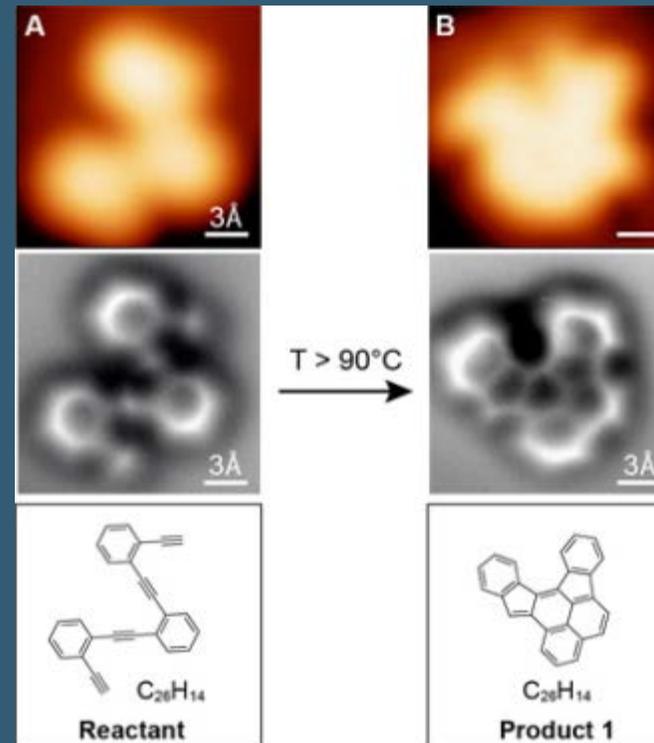


ATOMIC FORCE MICROSCOPE



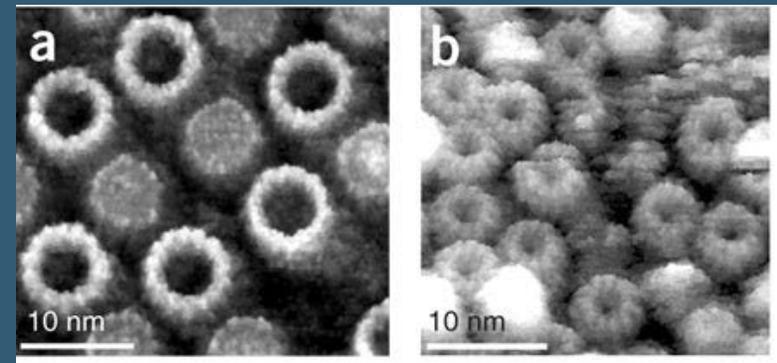
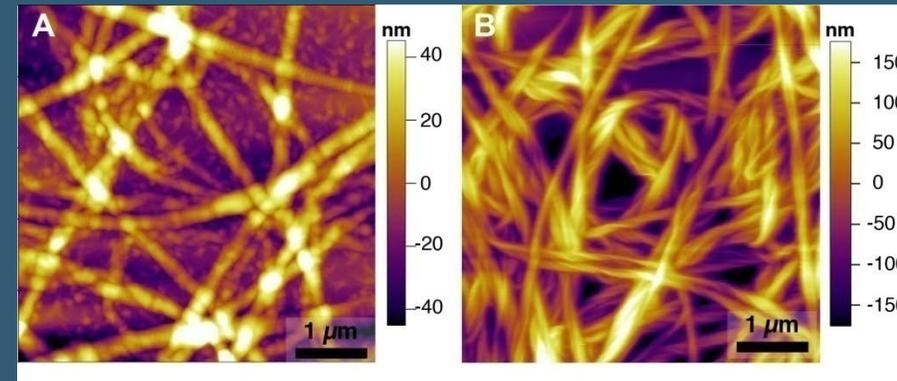
APPLICATIONS OF AFM

- Take Atomic-Scale Picture of Chemical Bonds
- Bond length and molecular structure



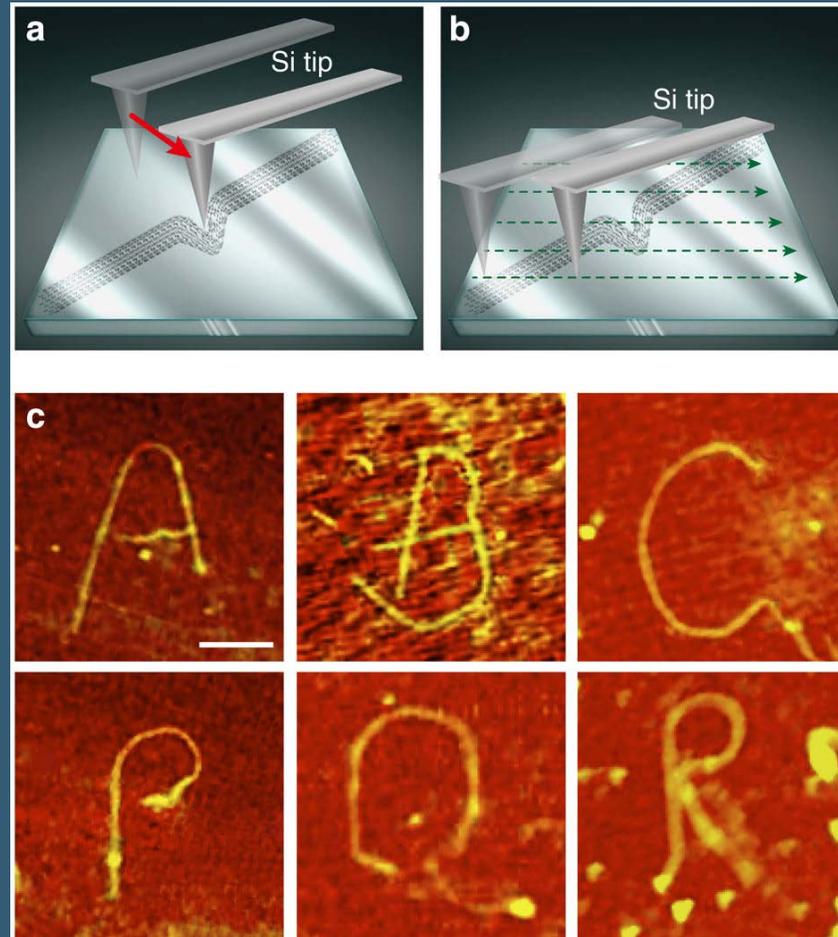
APPLICATIONS OF AFM

- Take Atomic-Scale Picture of biological specimen
 - Collagen fibril matrices
 - Native membrane proteins
- Size, Diameter, Physical and chemical properties



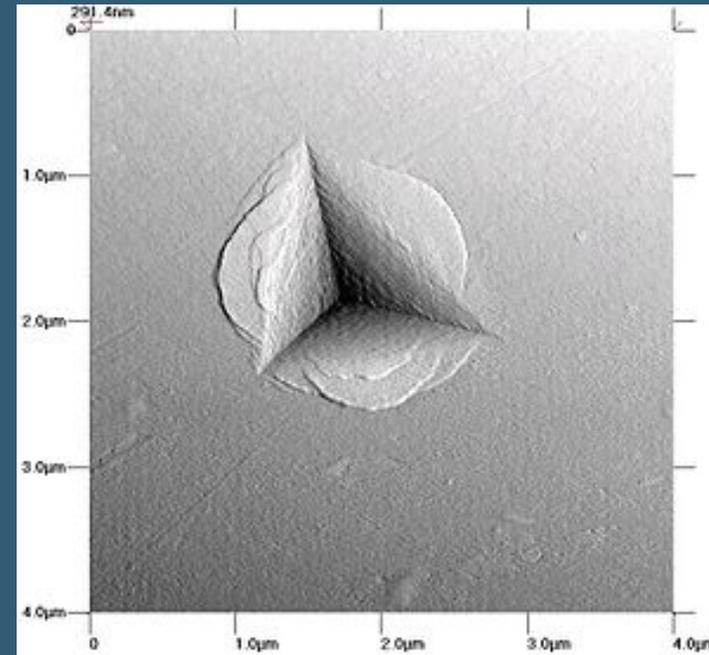
APPLICATIONS OF AFM

- Manipulation
- Lithography



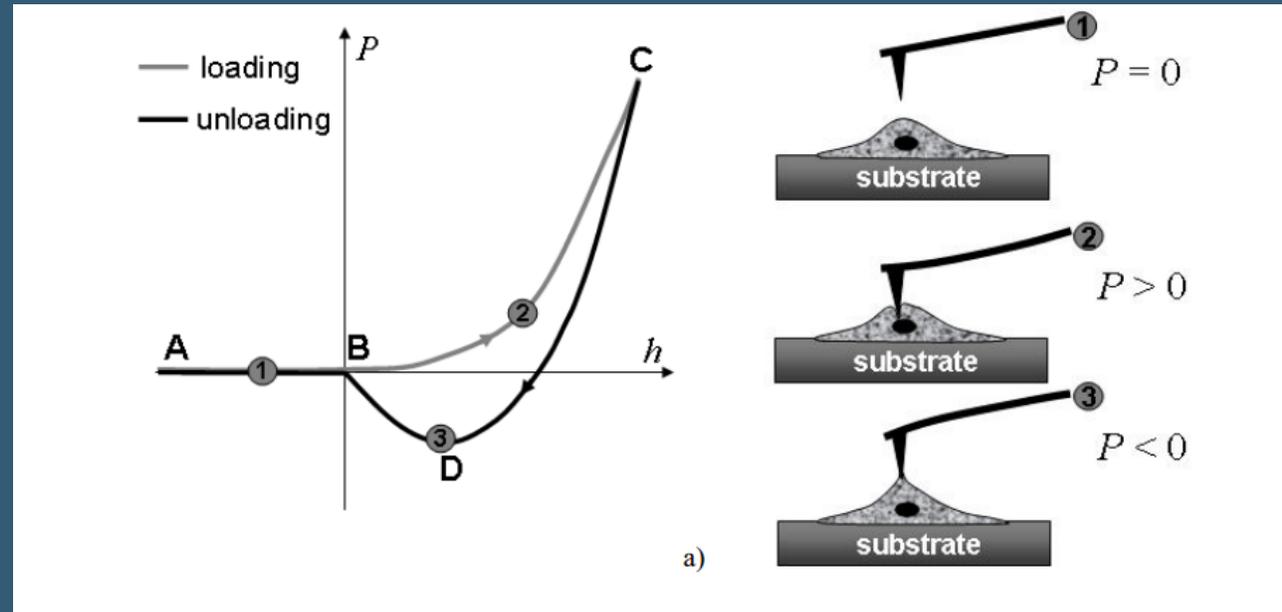
APPLICATIONS OF AFM

- Material properties of substrates
 - Indentation
- Size, depth  Hardness



APPLICATIONS OF AFM

- Nano-force measurement





สถาบันมาตรวิทยาแห่งชาติ
National Institute of Metrology (Thailand)

THANK YOU

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